02 APR 2004

Figure 1

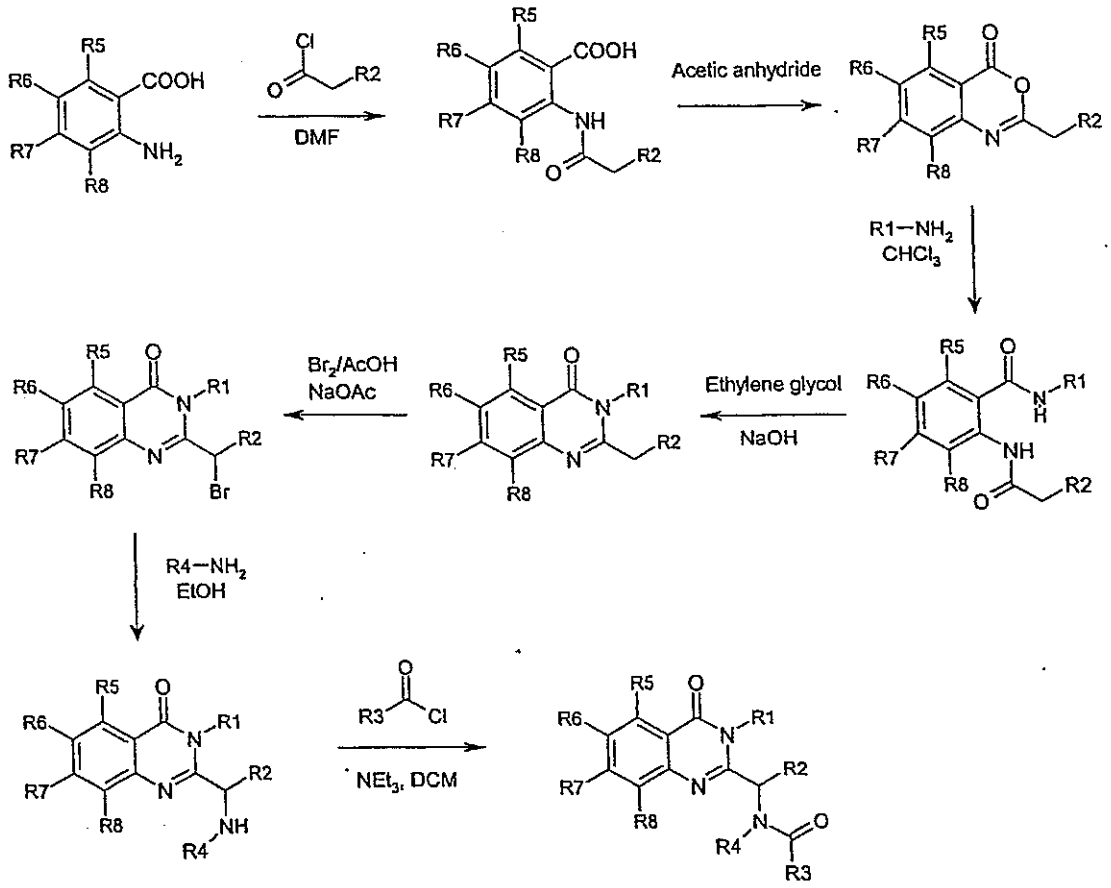


Figure 2

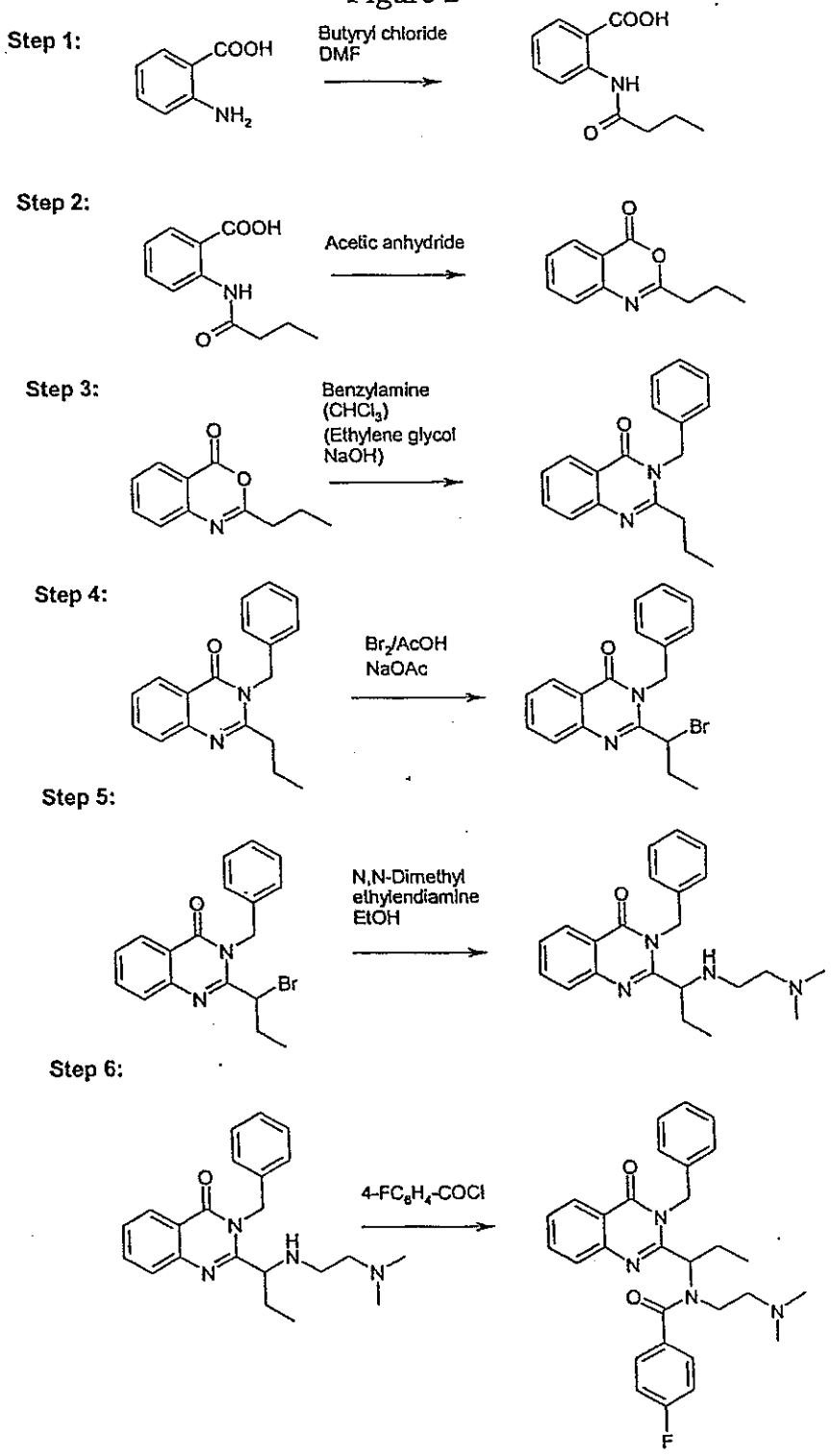
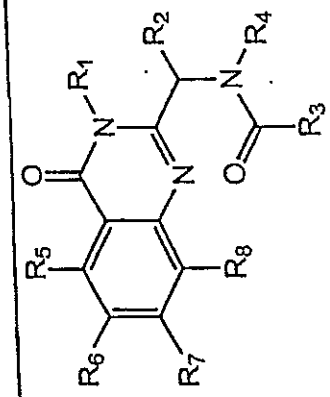

Step 1:
COOH
NH2
Butyryl chloride
DMF
COOH
NH
O
Step 2:
COOH
NH
O
Acetic anhydride
O
O
N
Step 3:
O
O
N
Benzylamine
(CHCl3)
(Ethylene glycol
NaOH)
O
N
N
Step 4:
O
N
N
Br2/AcOH
NaOAc
O
N
N
Br
Step 5:
O
N
N
Br
N,N-Dimethyl
ethylendiamine
EtOH
O
N
N
H
N
N
Step 6:
O
N
N
H
N
N
4-FC6H4-COCl
O
N
N
N
O
F

Figure 3



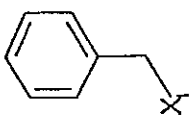
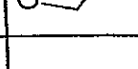
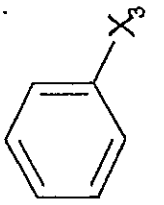
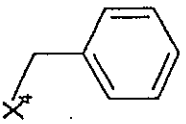
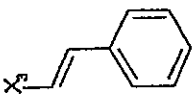
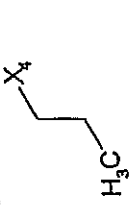
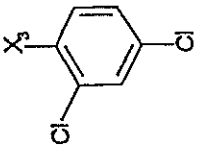
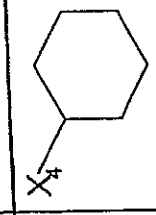
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
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								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

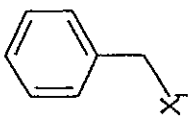
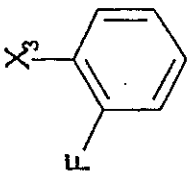
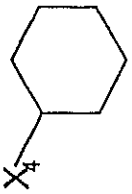
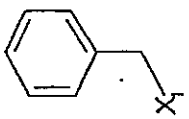
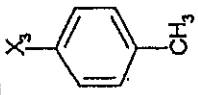
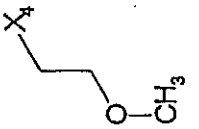
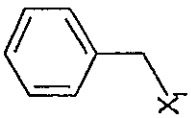
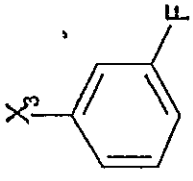
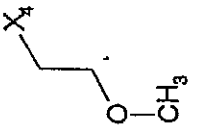
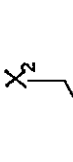
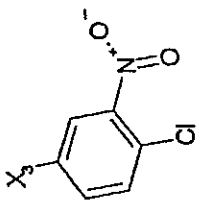
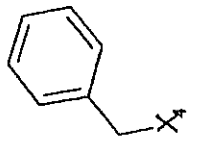
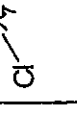
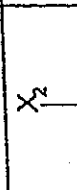
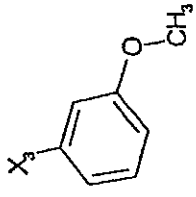
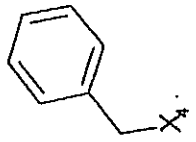
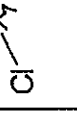
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								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

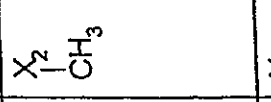
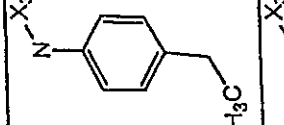
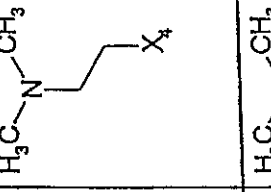
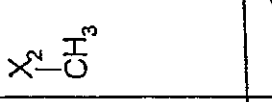
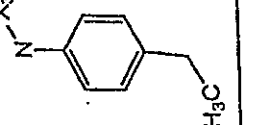
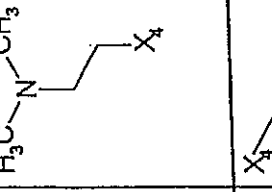
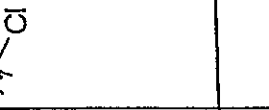
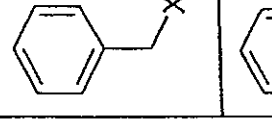
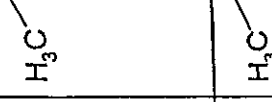
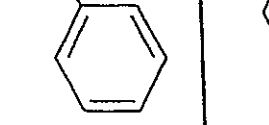
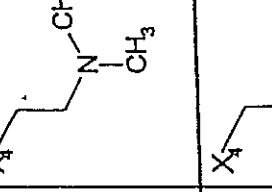
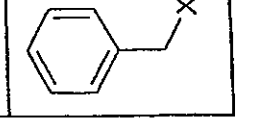
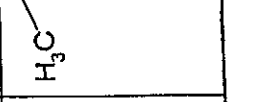
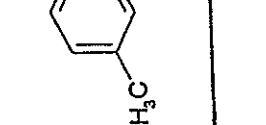
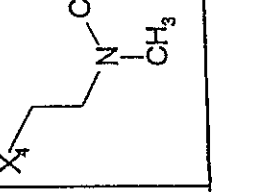
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
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								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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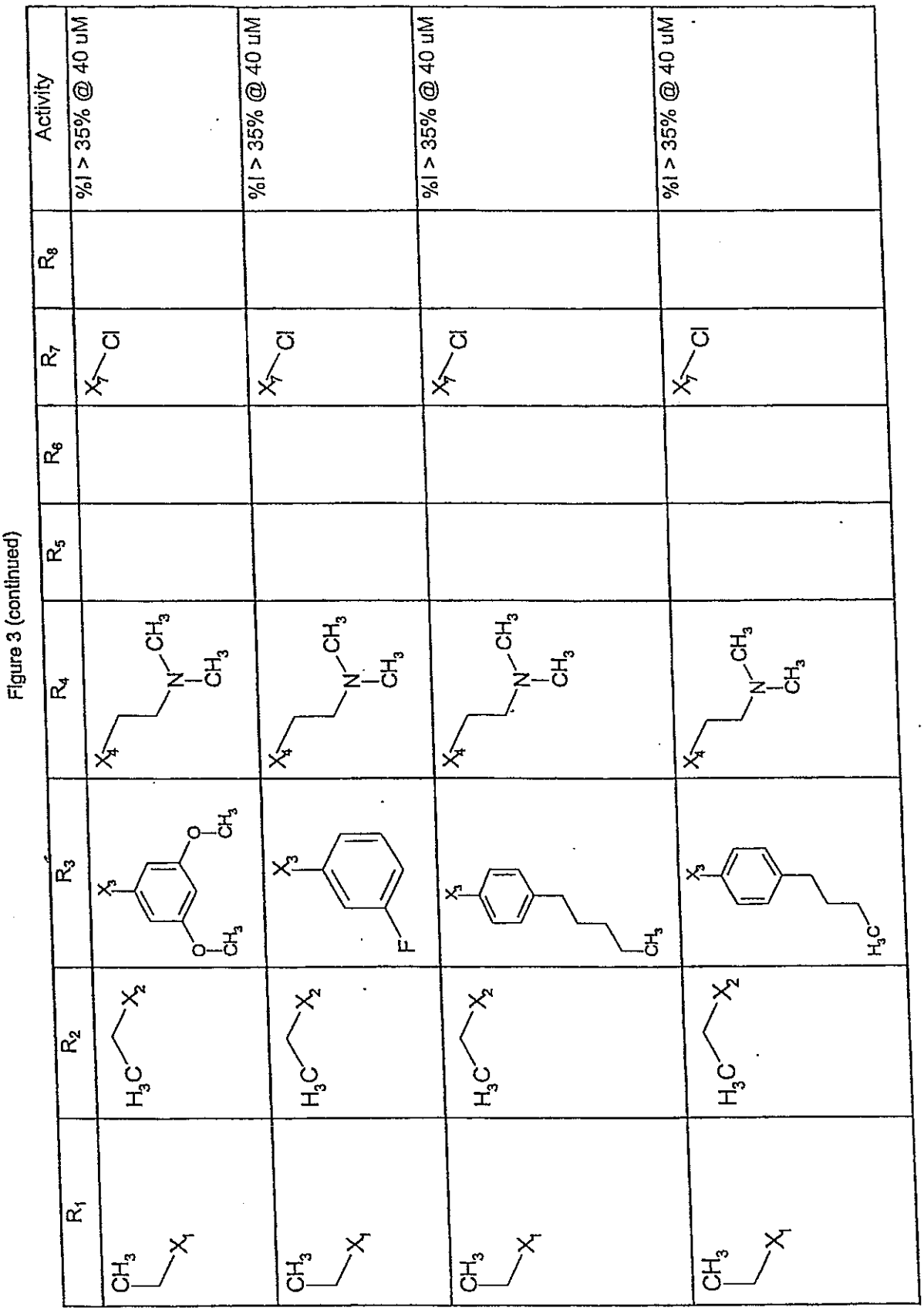
Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
CH_3—X_1	H_3C—X_2	X_3 with O—CH_3 and O—CH_3	X_4—N(CH_3)—CH_3			X_7—Cl		%I > 35% @ 40 uM
CH_3—X_1	H_3C—X_2	X_3 with F	X_4—N(CH_3)—CH_3			X_7—Cl		%I > 35% @ 40 uM
CH_3—X_1	H_3C—X_2	X_3 with CH_3	X_4—N(CH_3)—CH_3			X_7—Cl		%I > 35% @ 40 uM
CH_3—X_1	H_3C—X_2	X_3 with H_3C	X_4—N(CH_3)—CH_3			X_7—Cl		%I > 35% @ 40 uM

Figure 3 (continued)

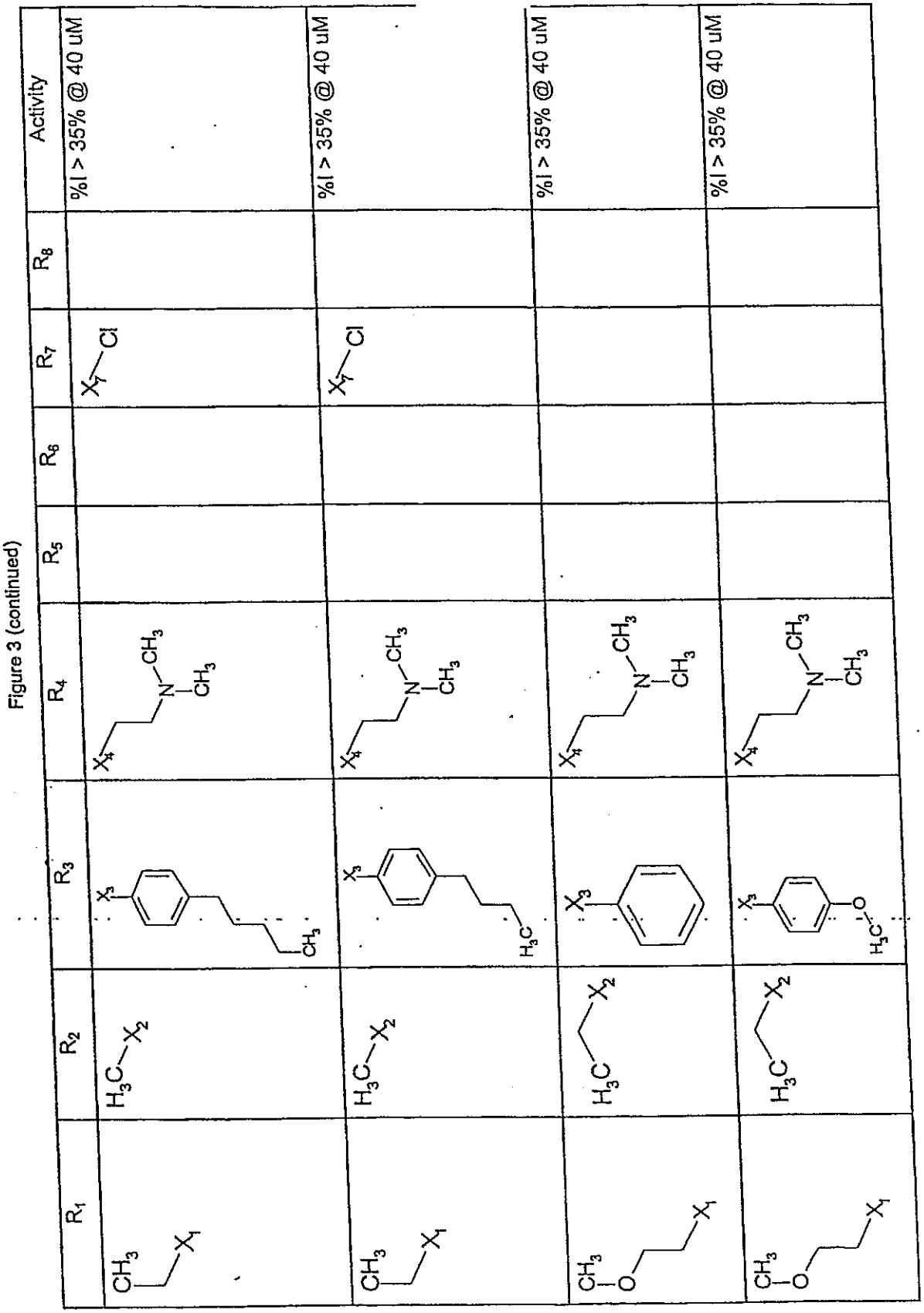


Figure 3 (continued)

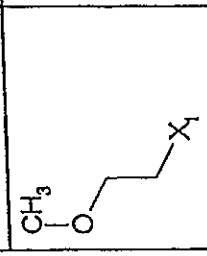
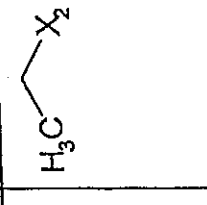
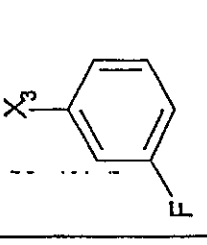
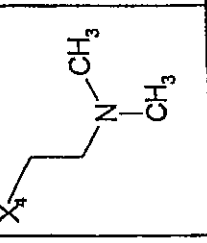
R1	R2	R3	R4	R5	R6	R7	R8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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Figure 3 (continued)

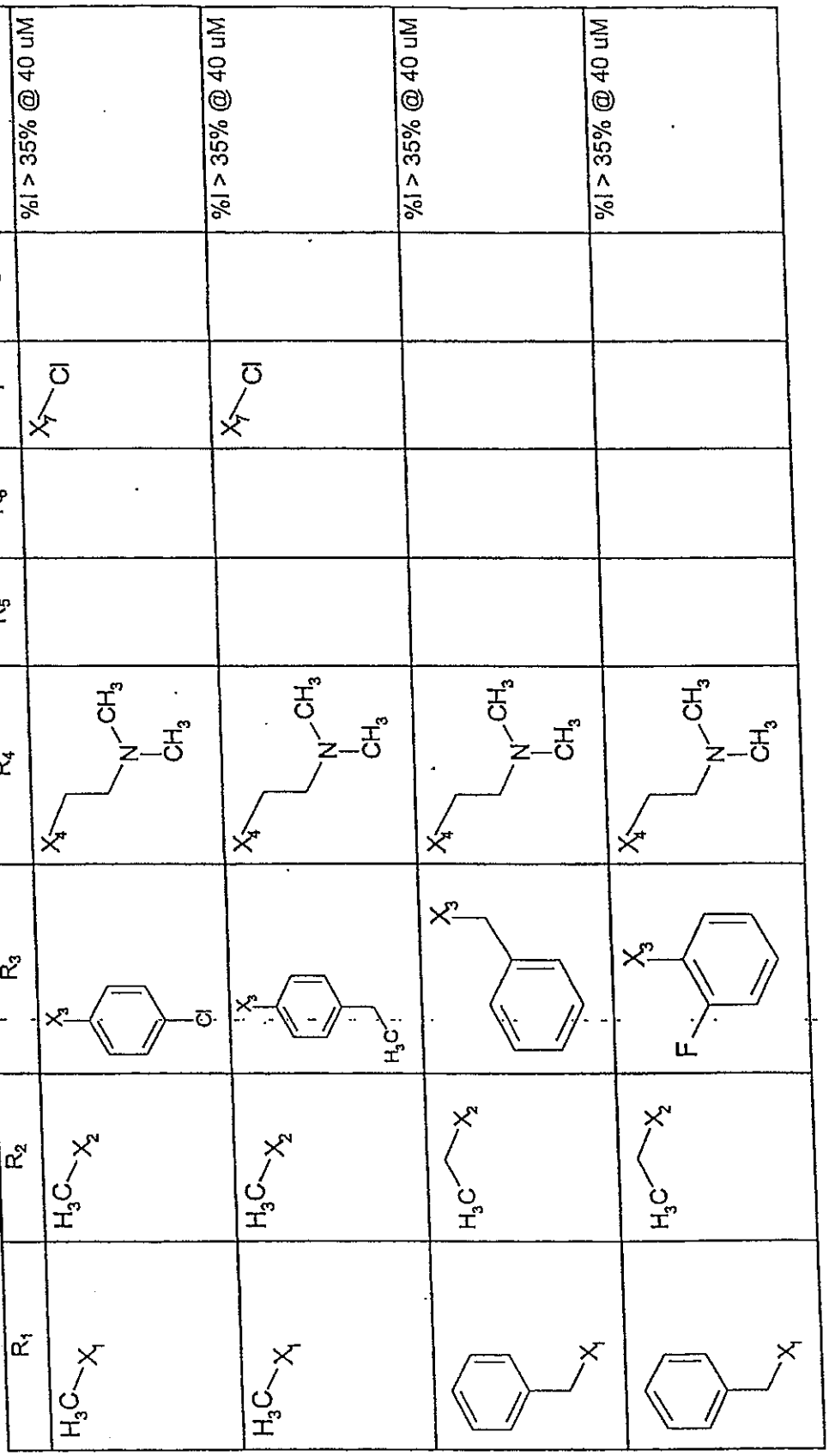
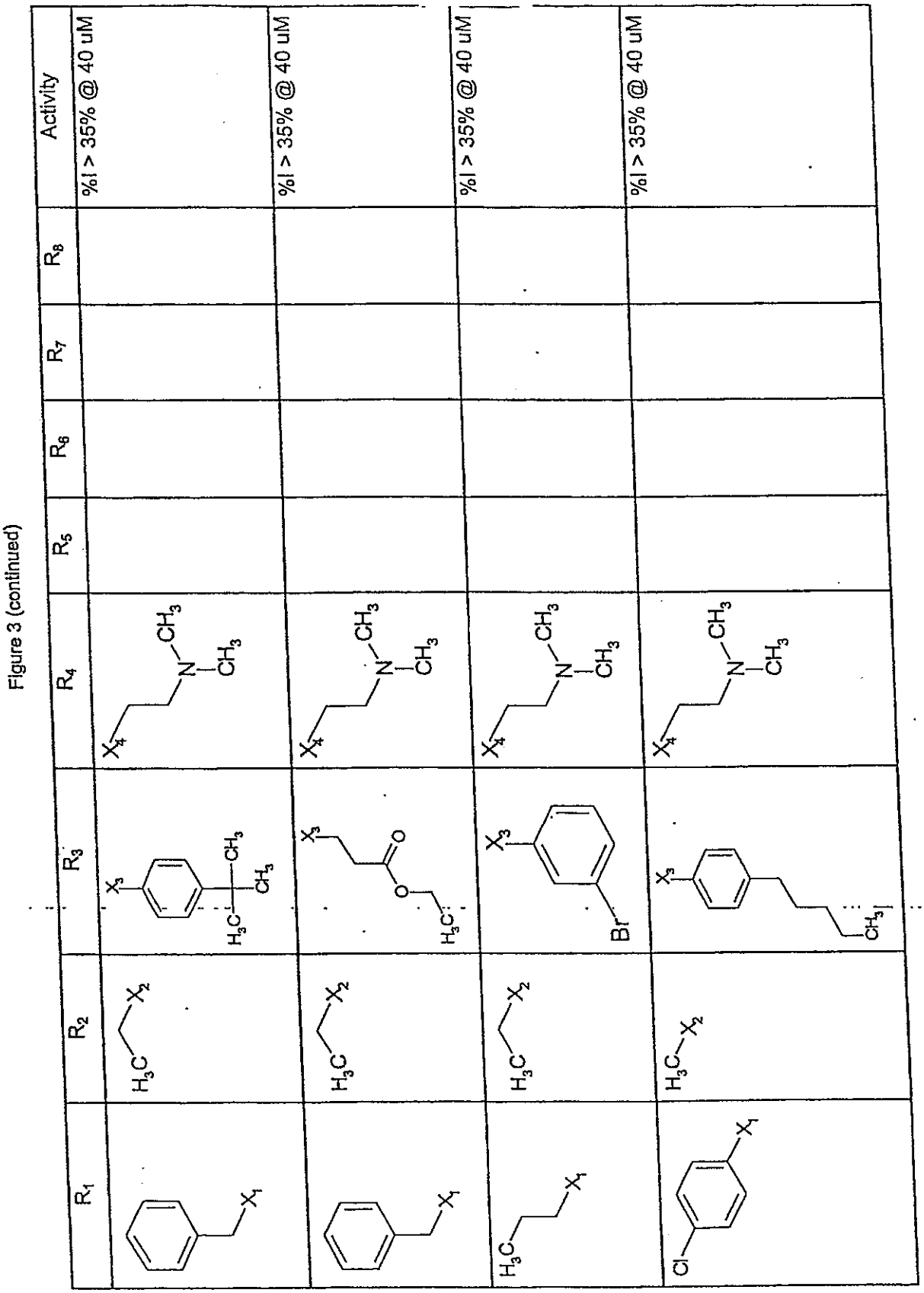
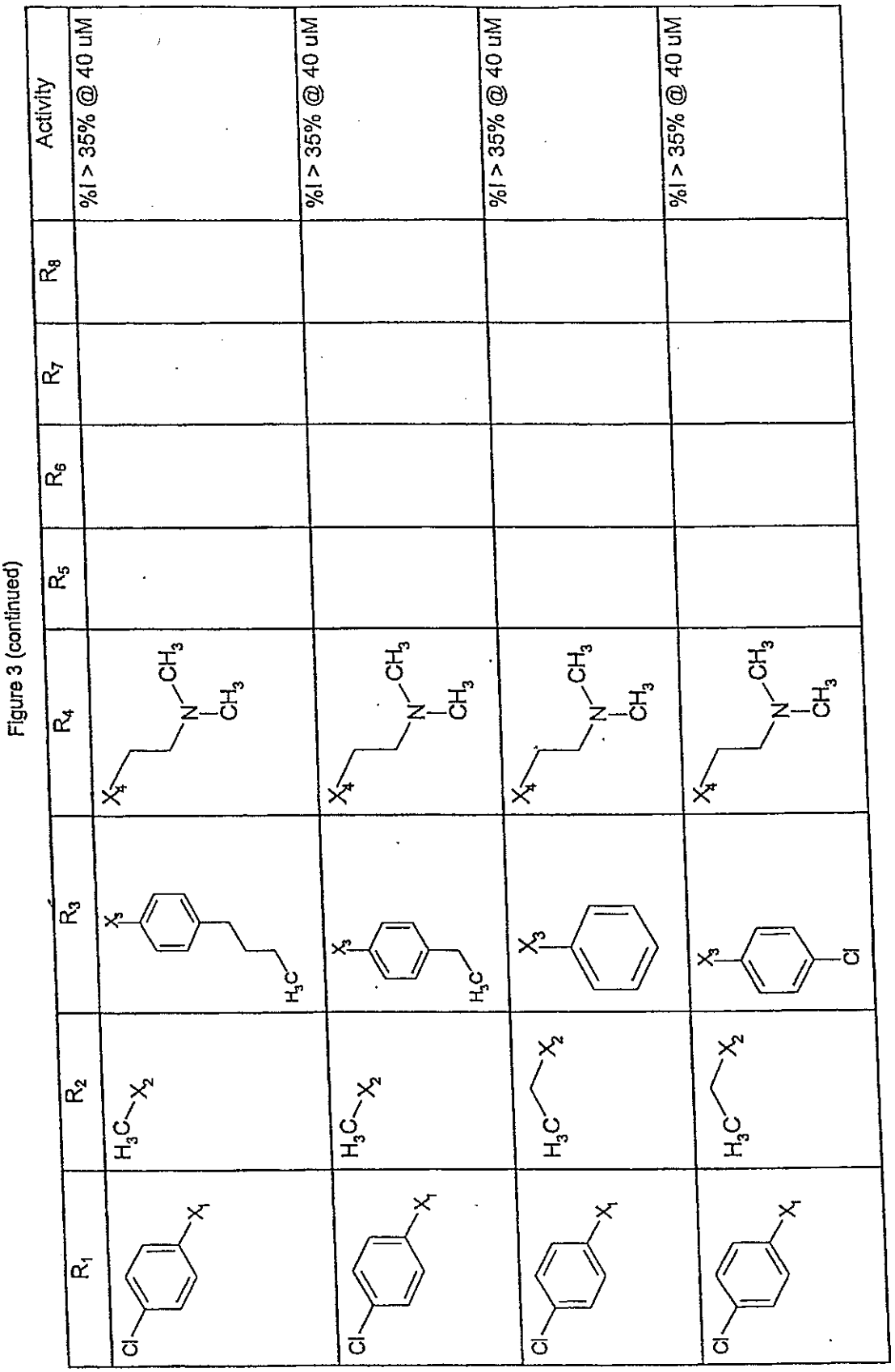


Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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Figure 3 (continued)

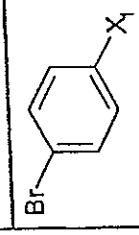
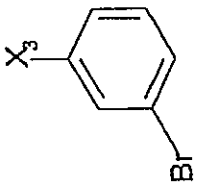
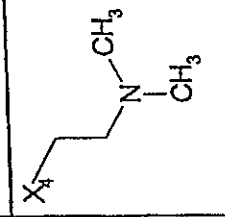
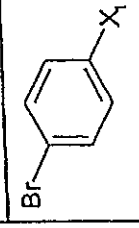
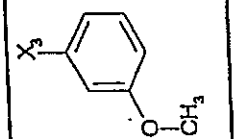
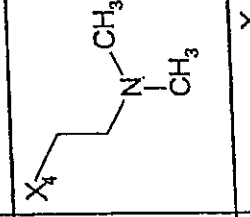
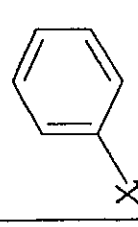
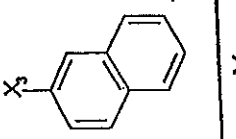
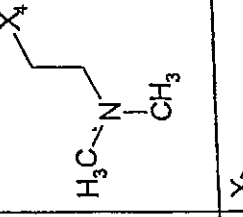
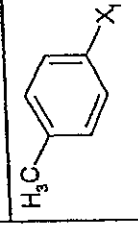
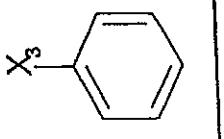
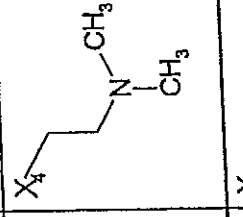
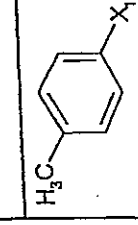
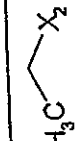
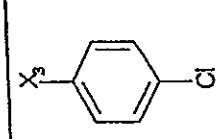
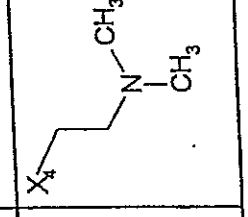
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

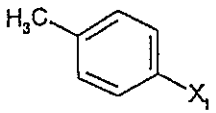
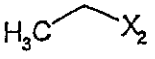
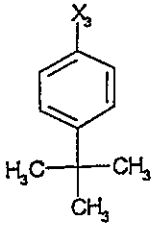
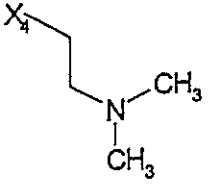
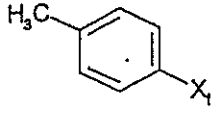
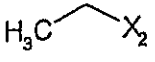
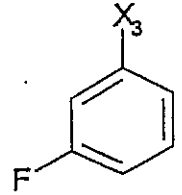
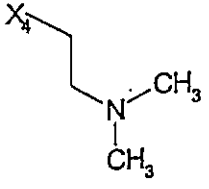
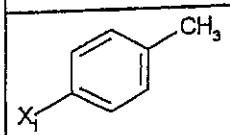
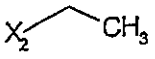
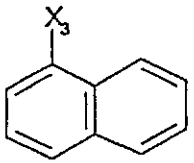
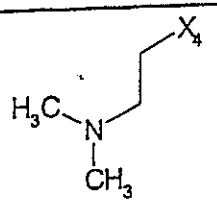
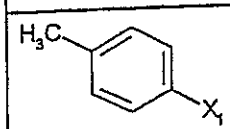
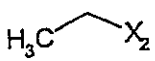
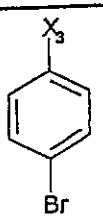
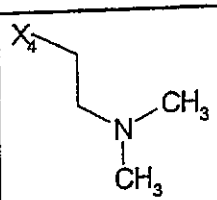
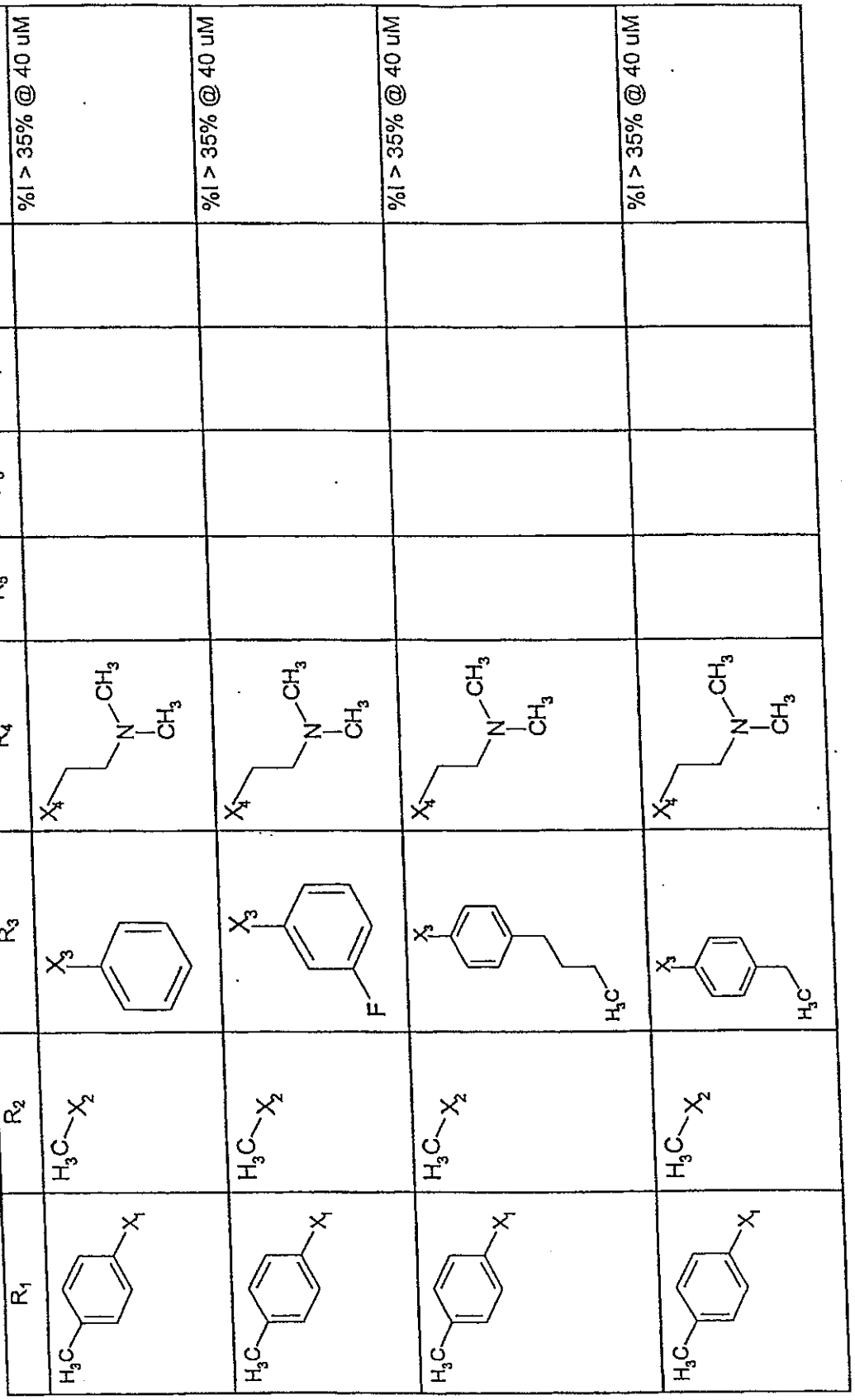
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
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								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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Figure 3 (continued)

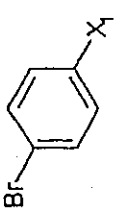
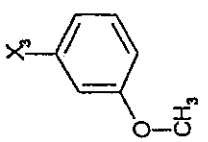
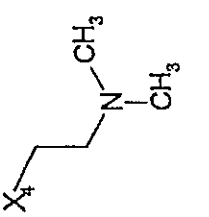
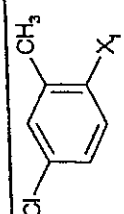
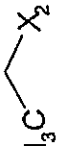
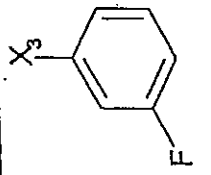
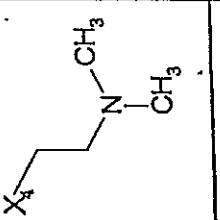
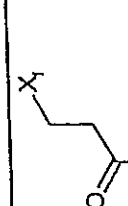
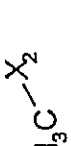
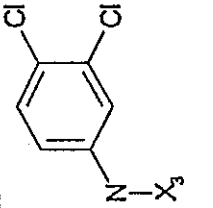
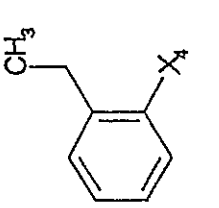
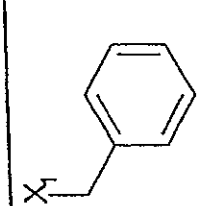
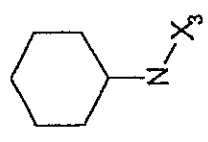
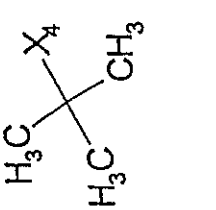
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM
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Figure 3 (continued)

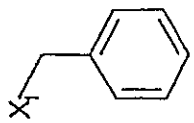
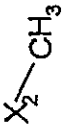
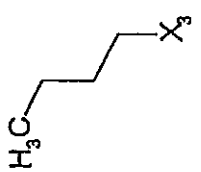
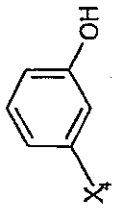
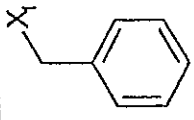
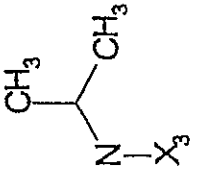
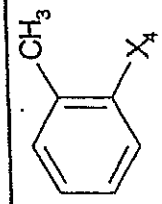
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								%I > 35% @ 40 uM
								%I > 35% @ 40 uM

Figure 3 (continued)

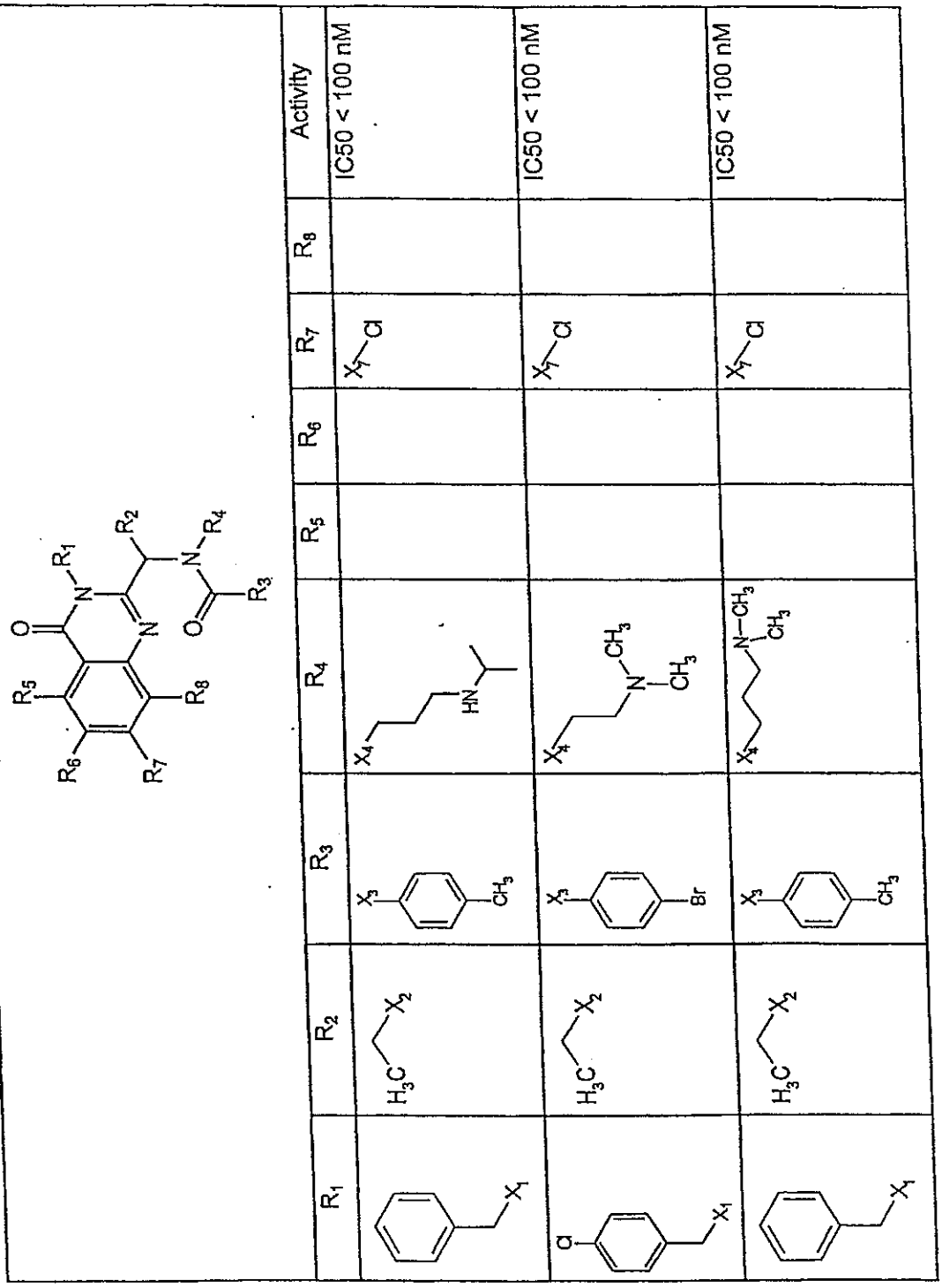
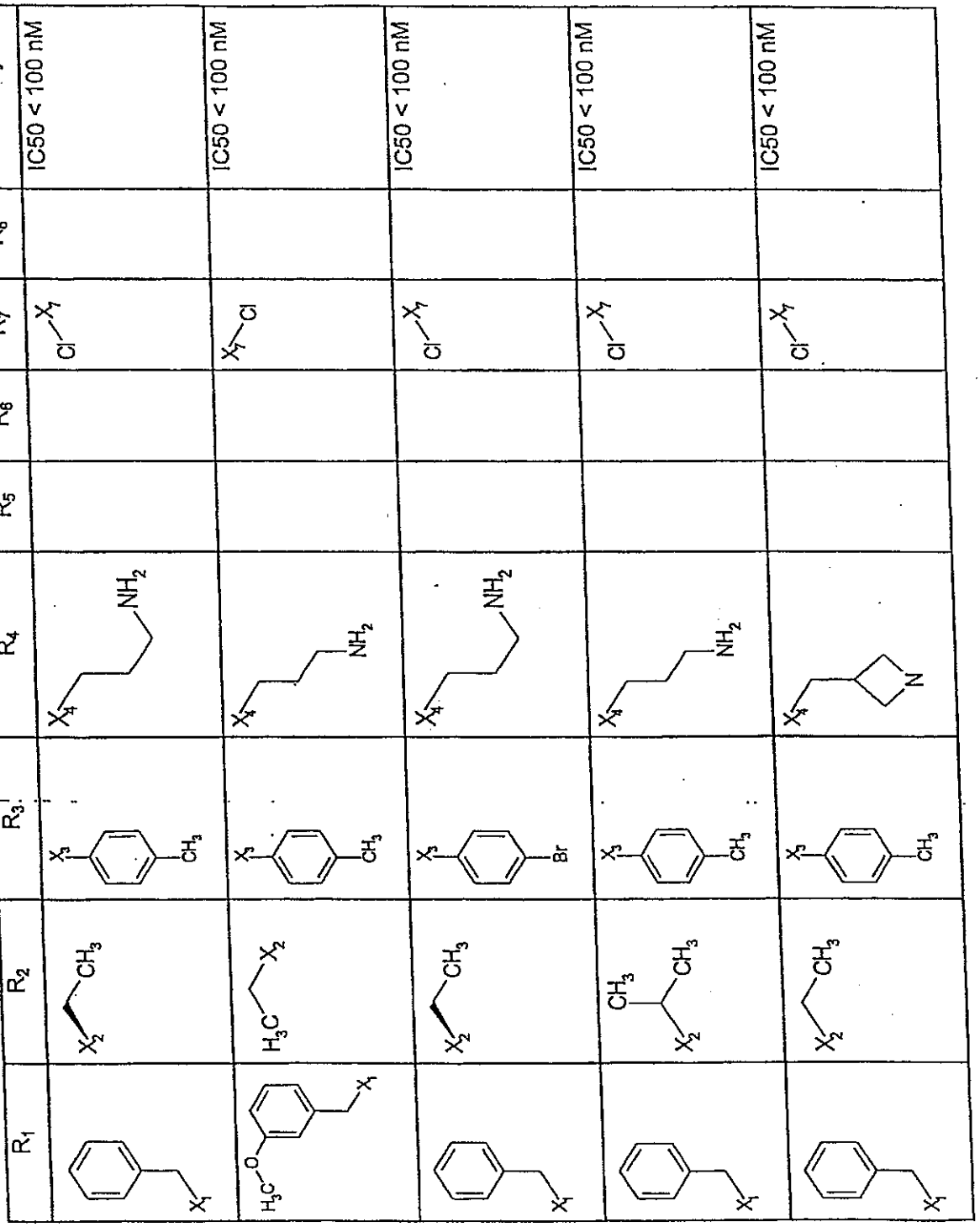


Figure 3 (continued)

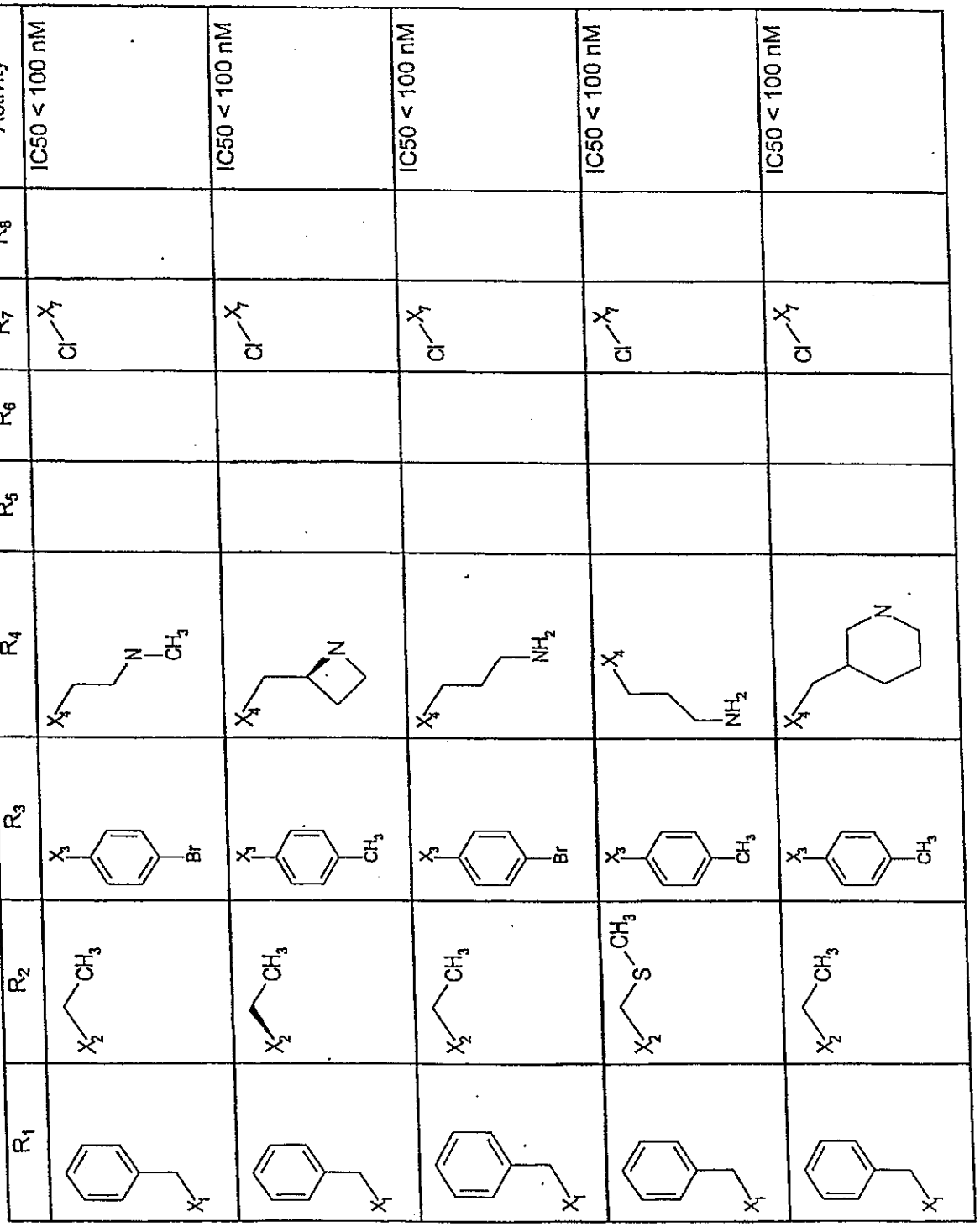


R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

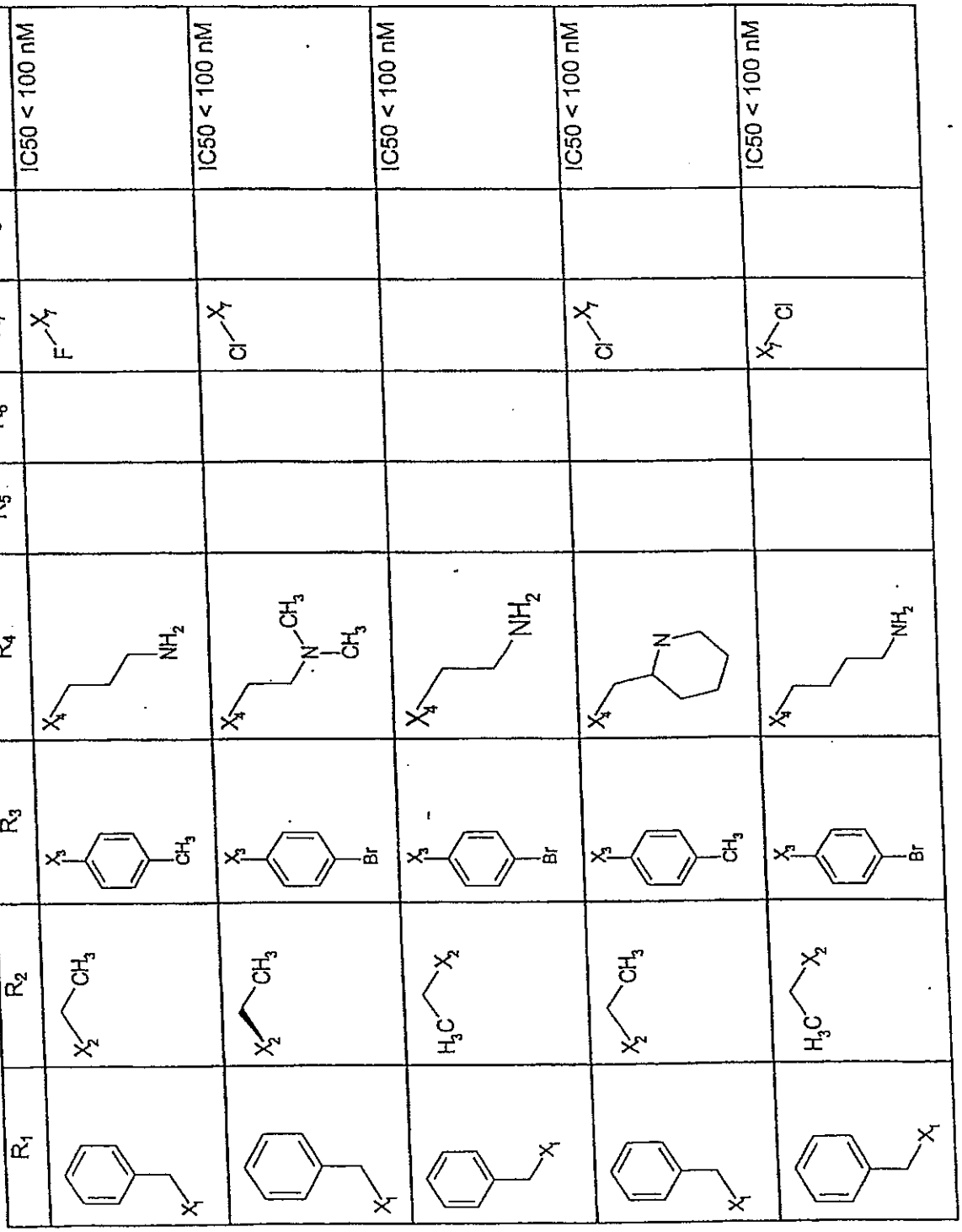
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
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Figure 3 (continued)

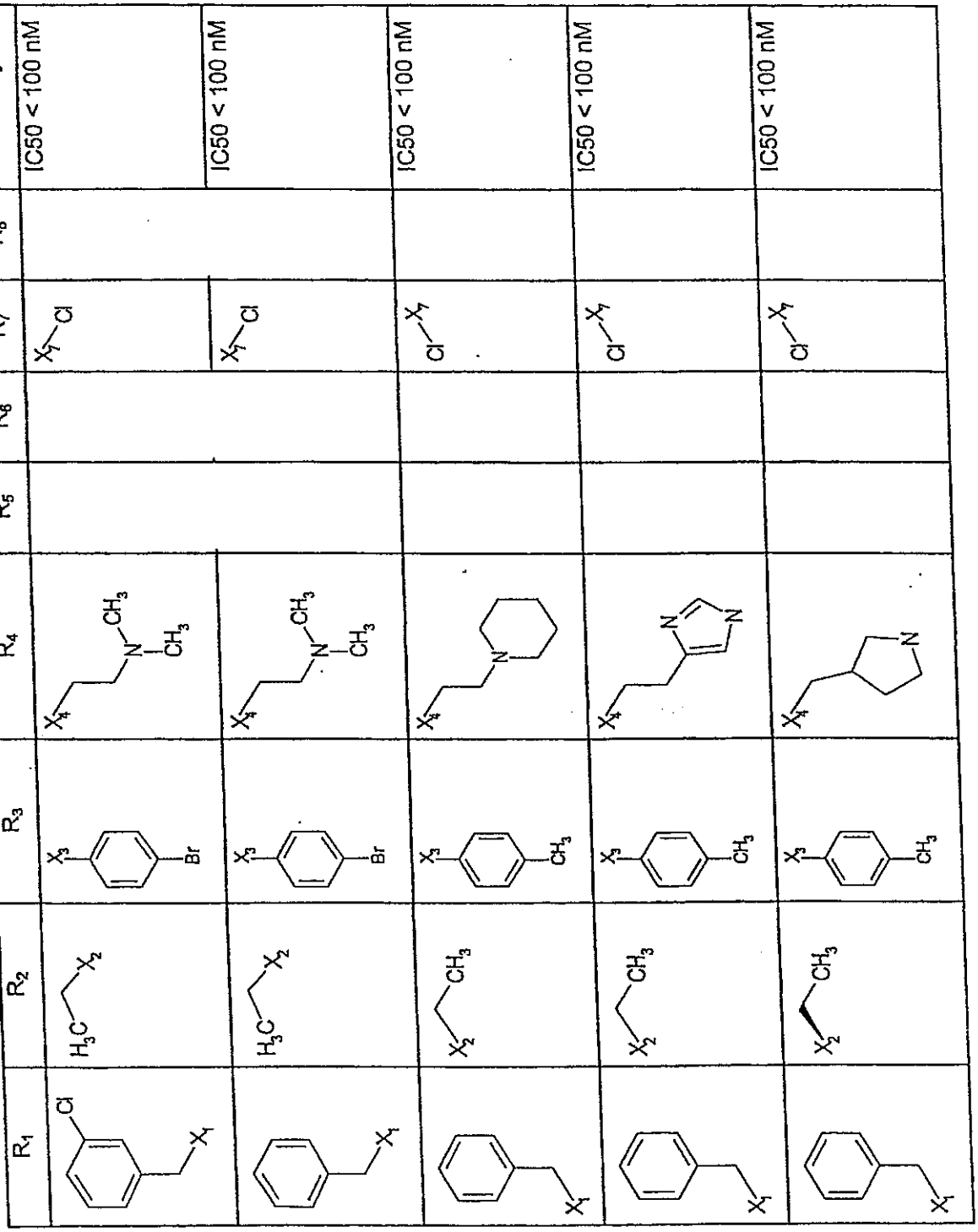


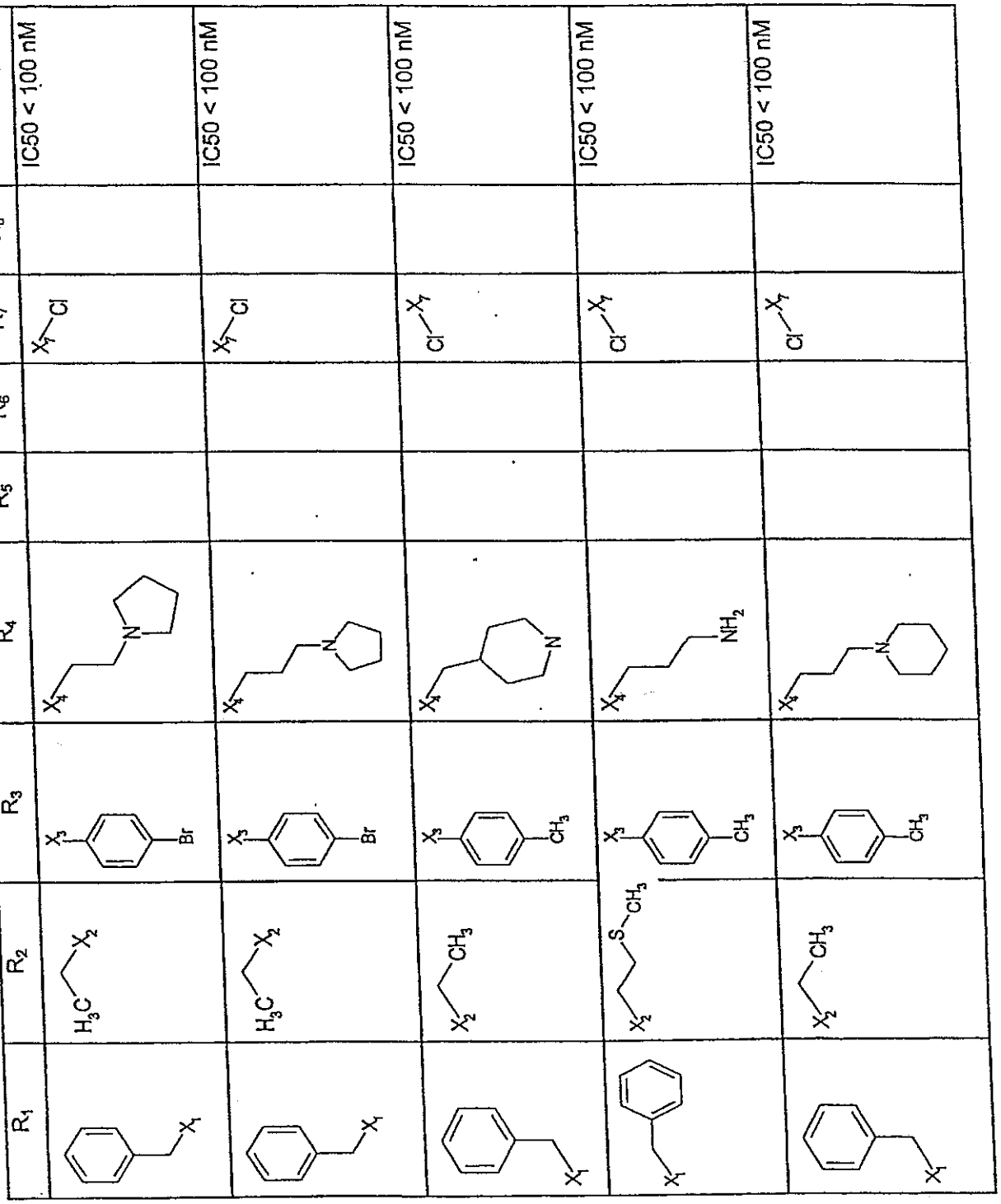
Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

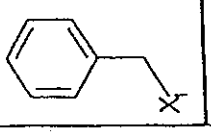
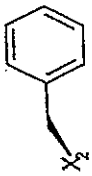
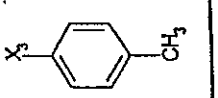
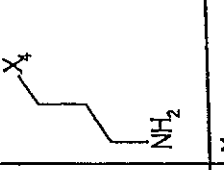
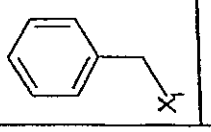
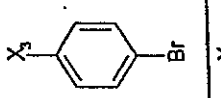
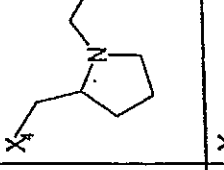
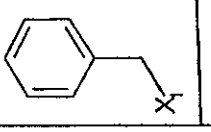
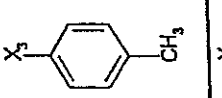
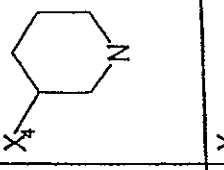
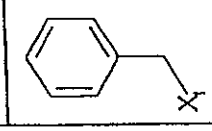
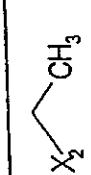
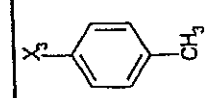
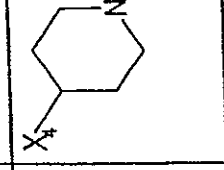
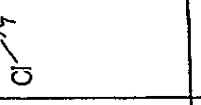
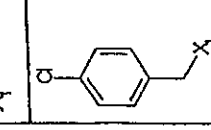
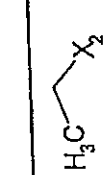
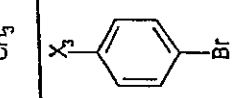
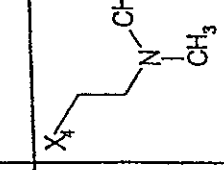
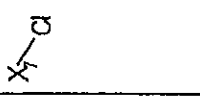
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

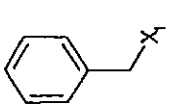
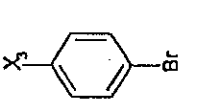
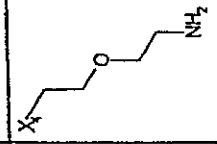
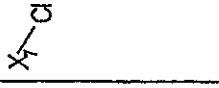
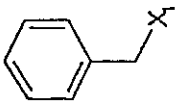
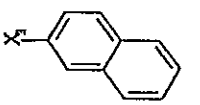
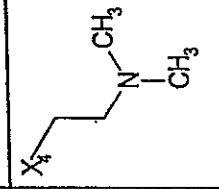
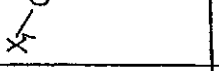
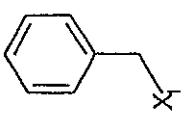
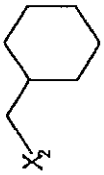
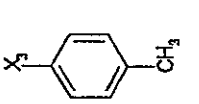
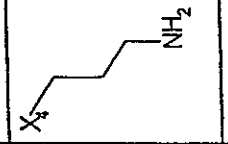
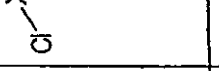
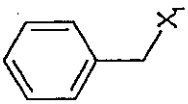
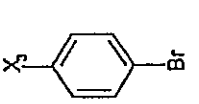
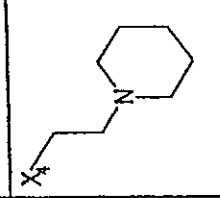
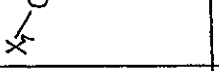
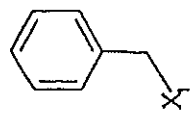
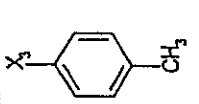
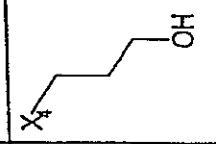
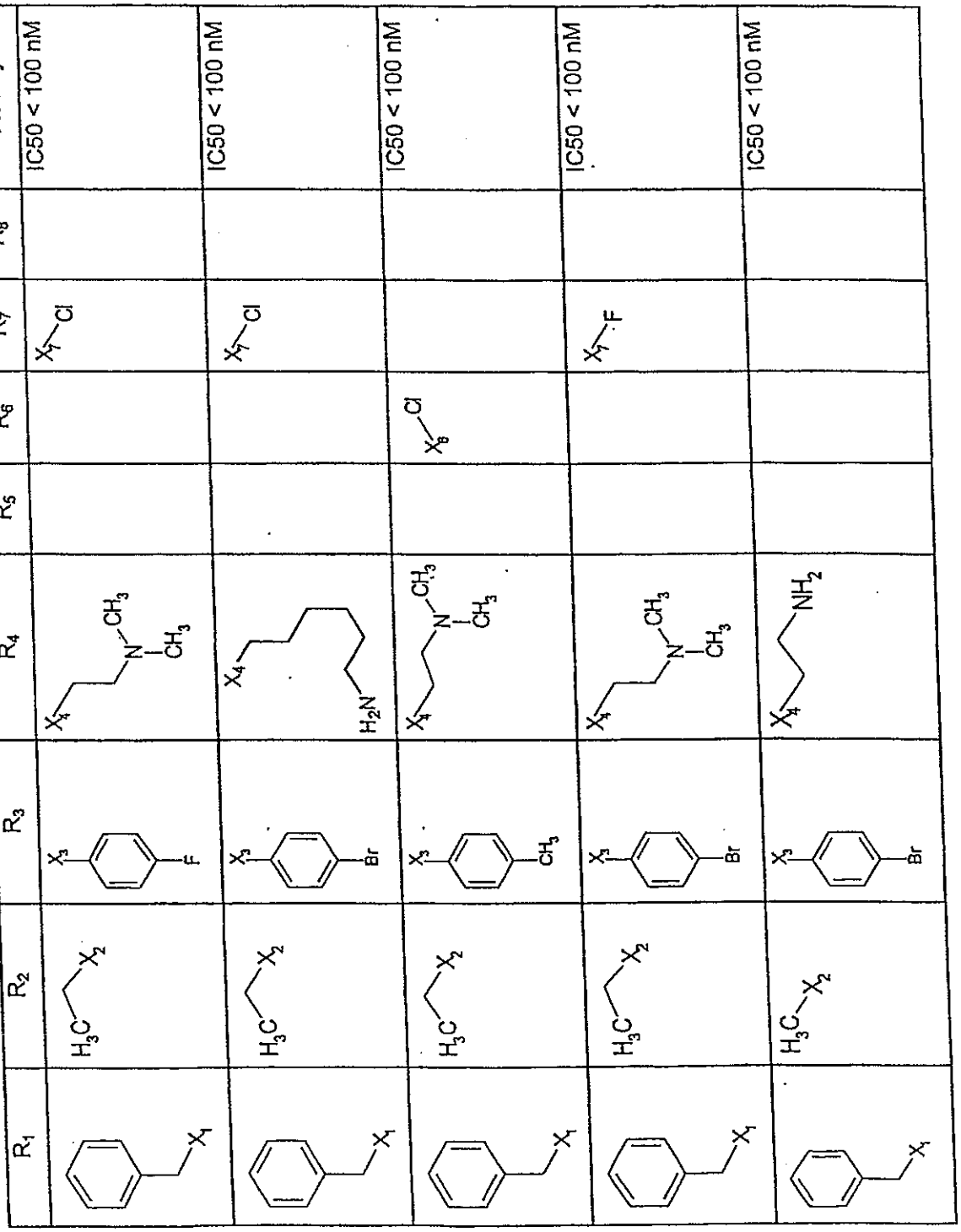
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

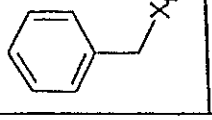
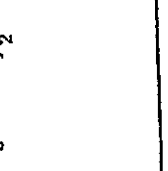
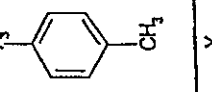
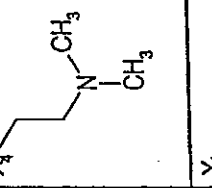
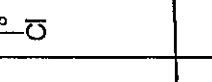
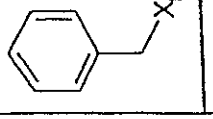
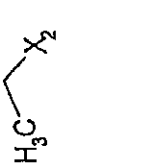
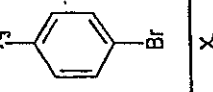
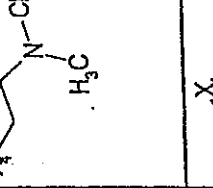
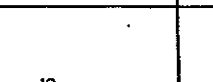
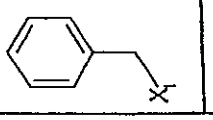
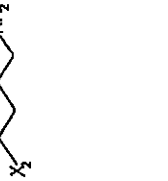
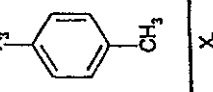
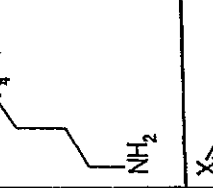
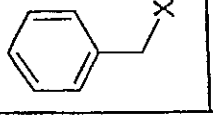
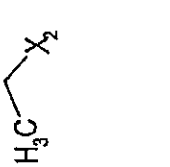
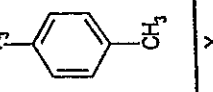
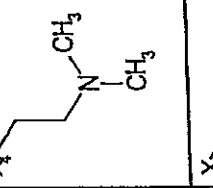
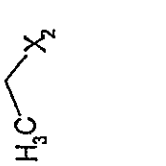
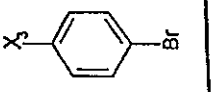
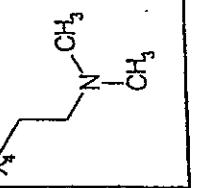
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 < 100 nM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 < 100 nM
								IC50 < 100 nM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

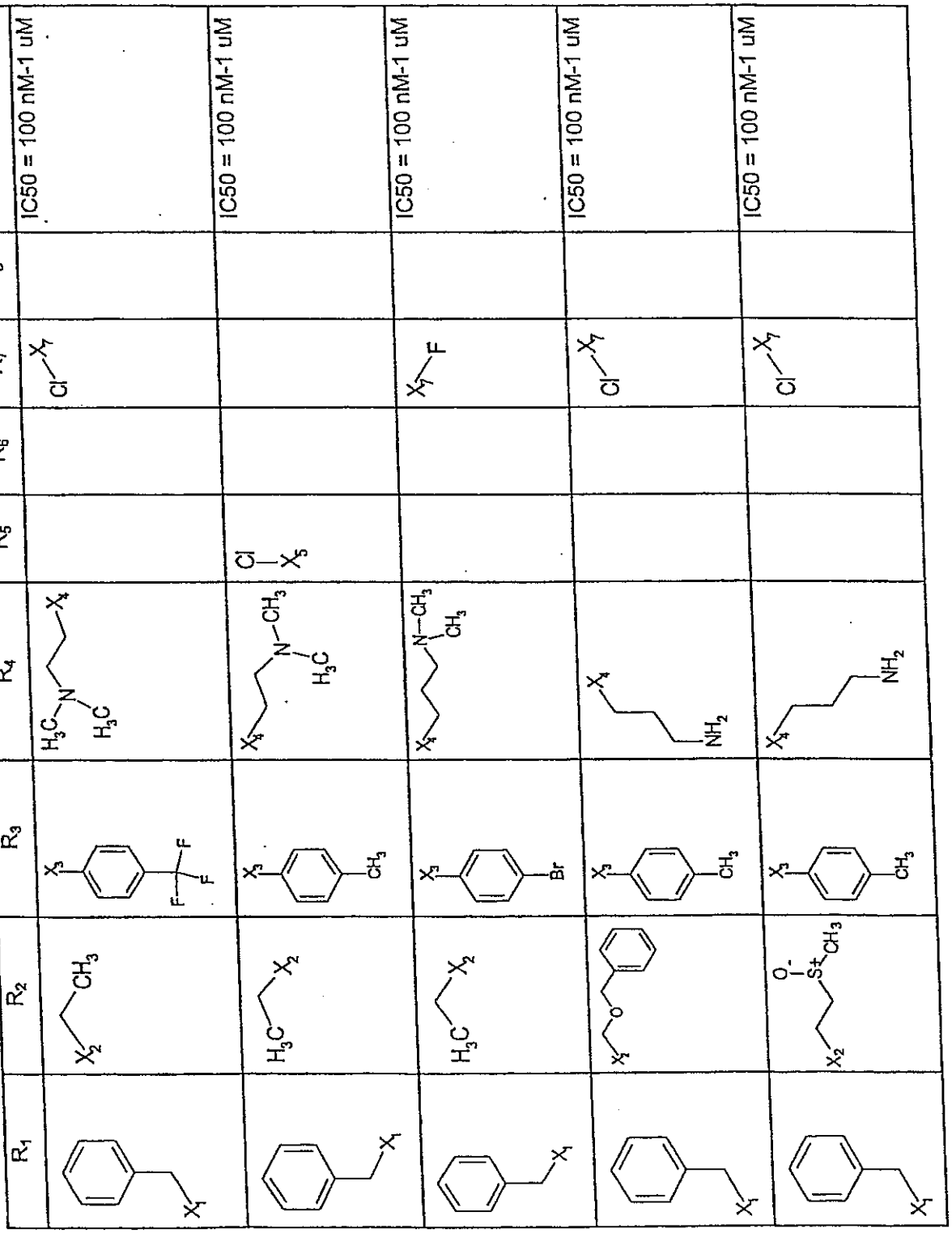
Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

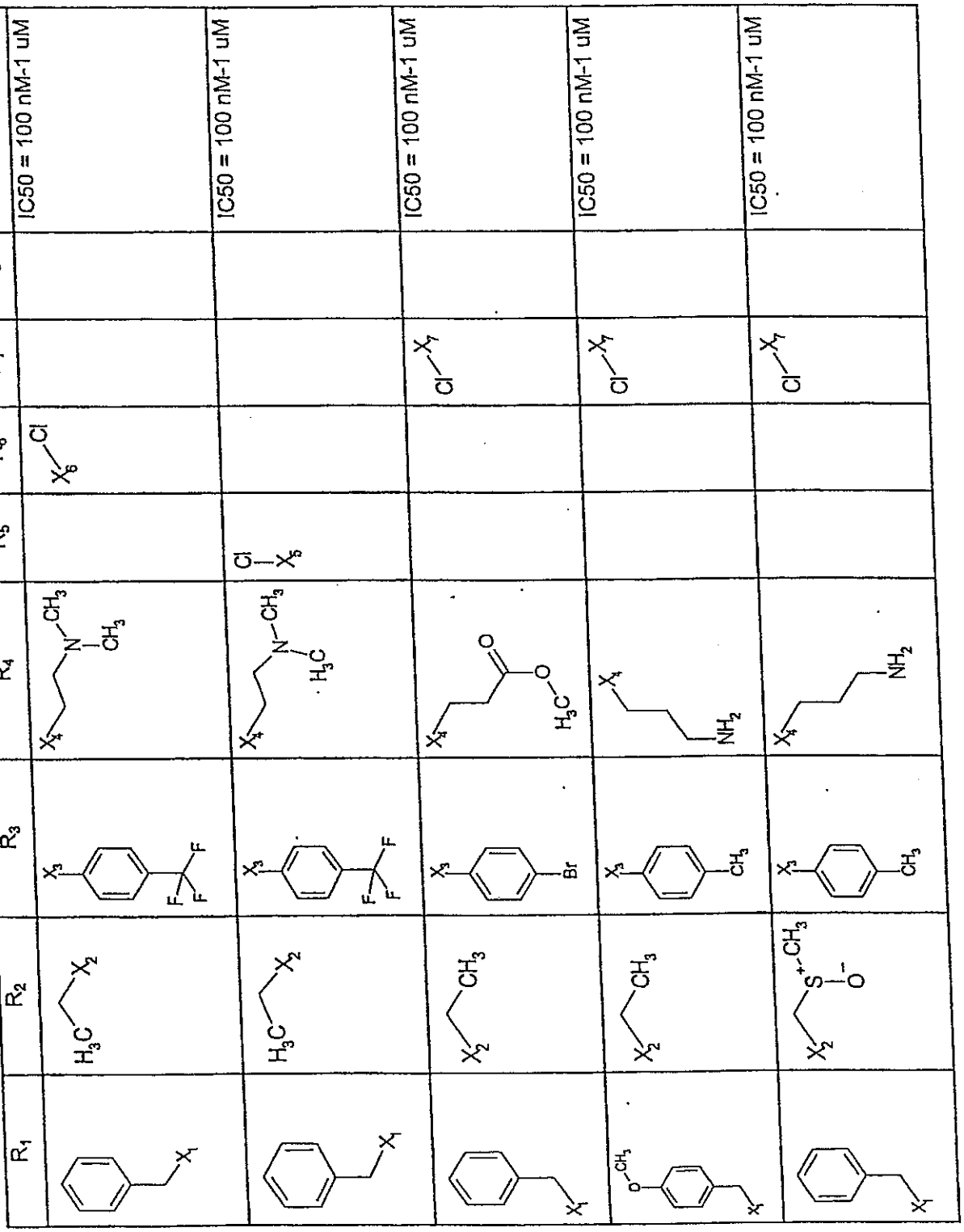


R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

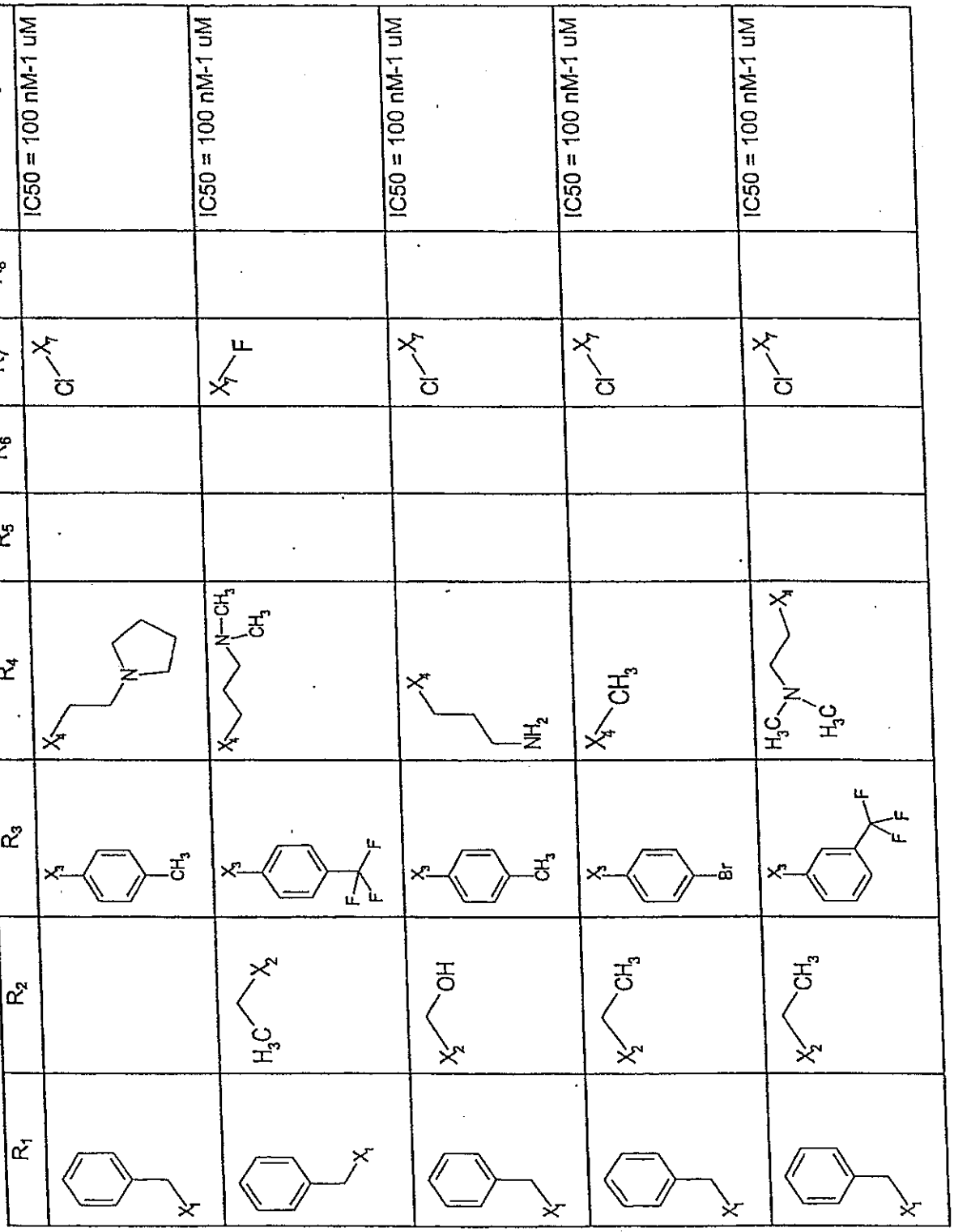
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_9	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

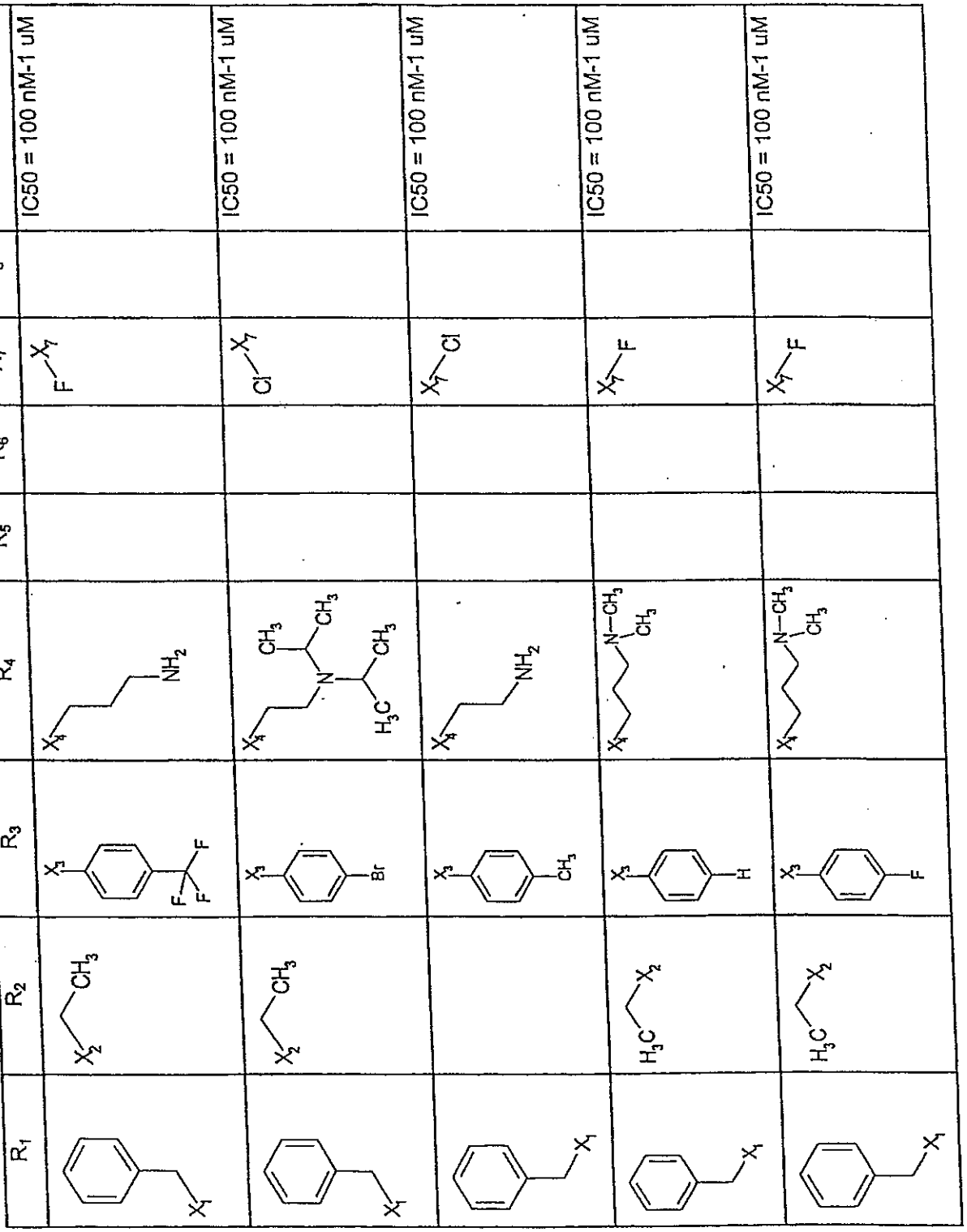
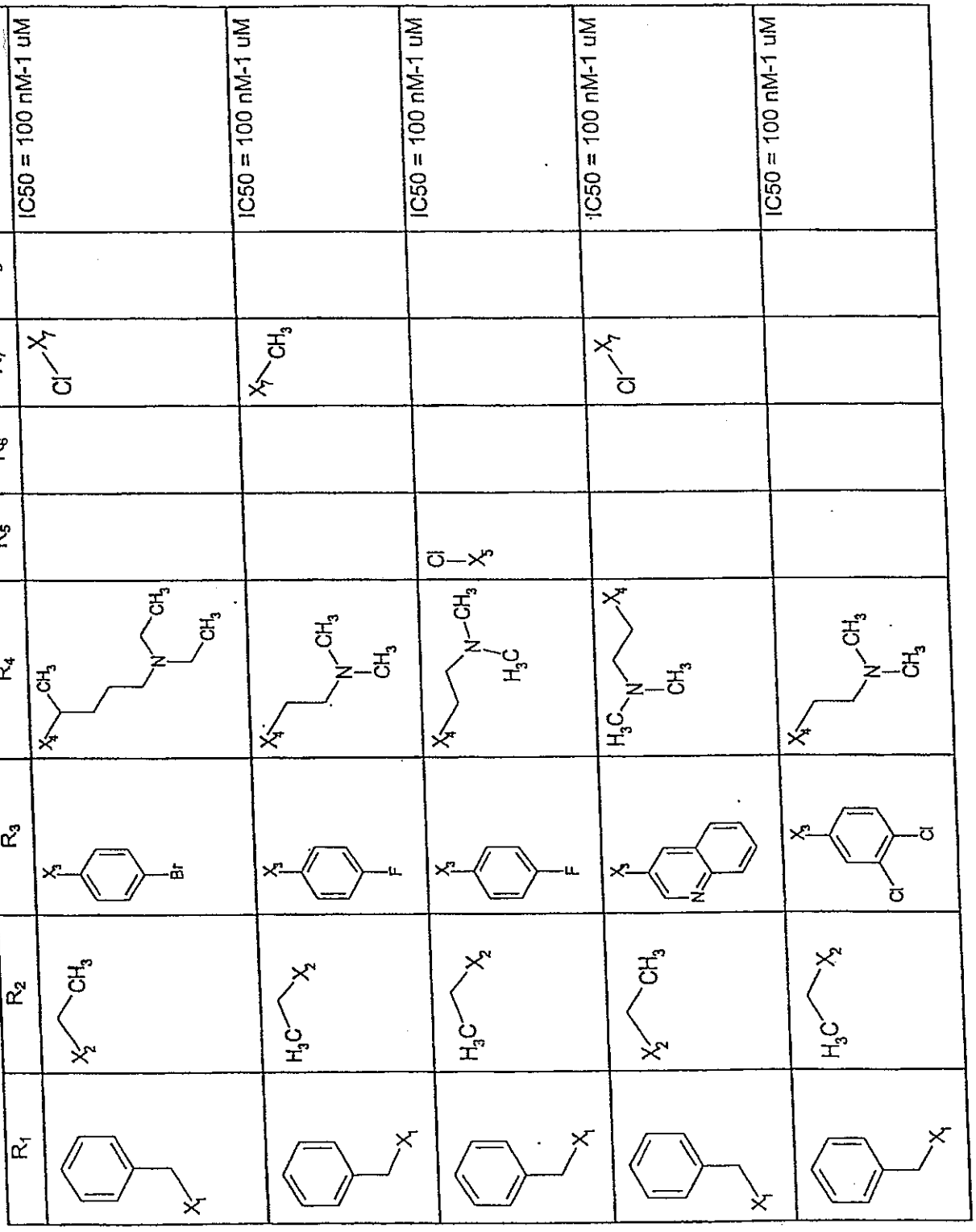


Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 100 nM-1 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

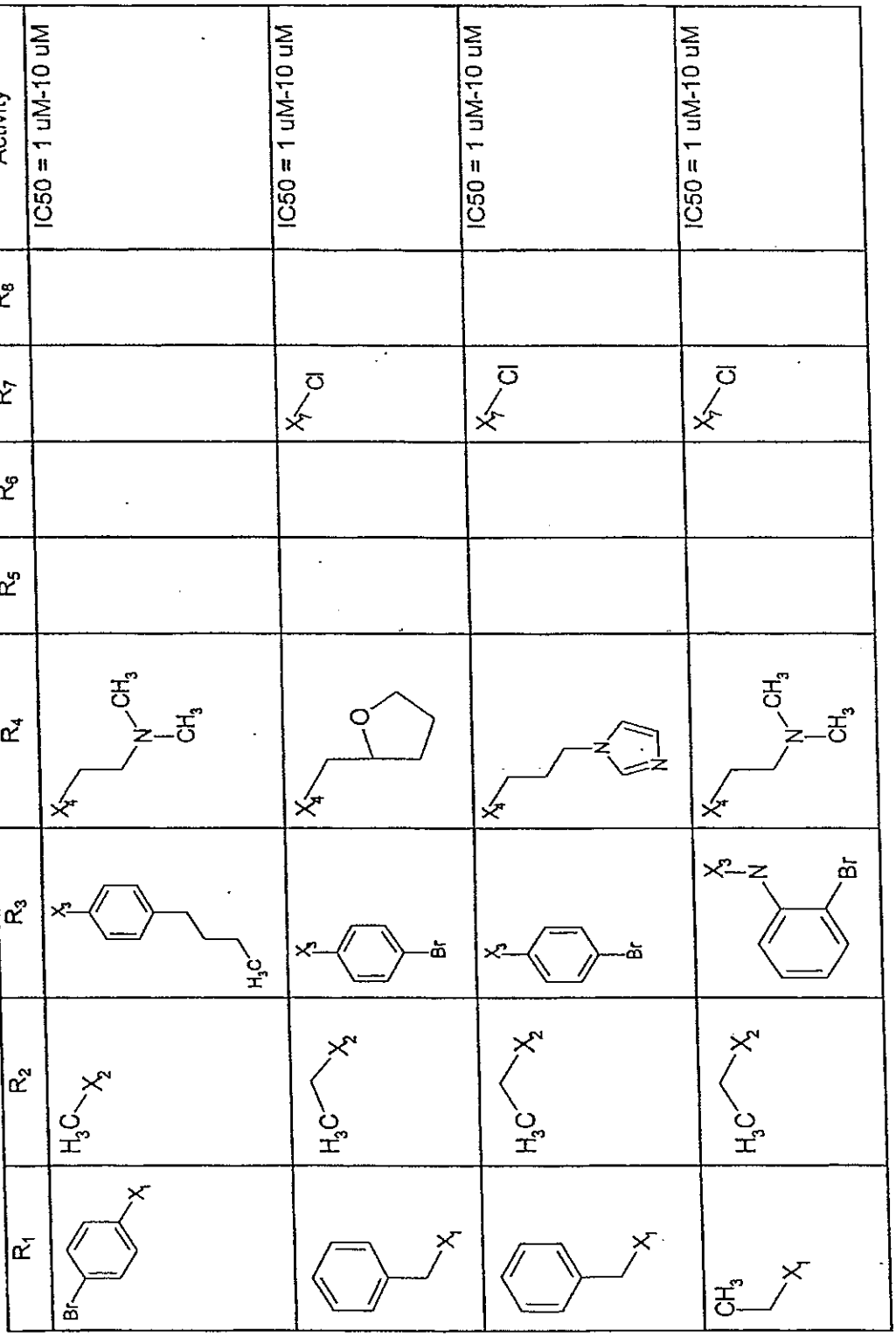


Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

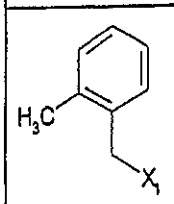
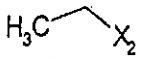
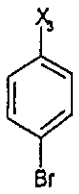
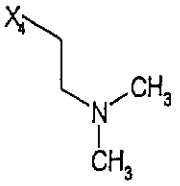
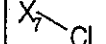
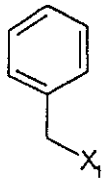
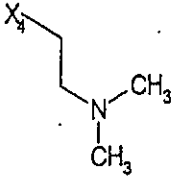
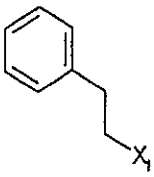
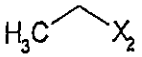
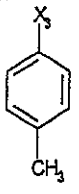
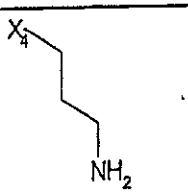
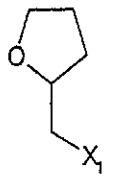
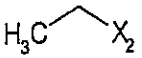
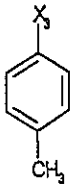
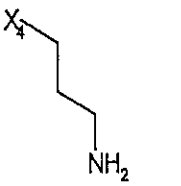
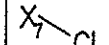
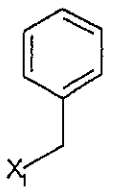
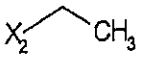
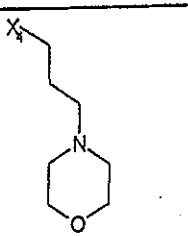
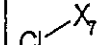
Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM

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Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 1 uM-10 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

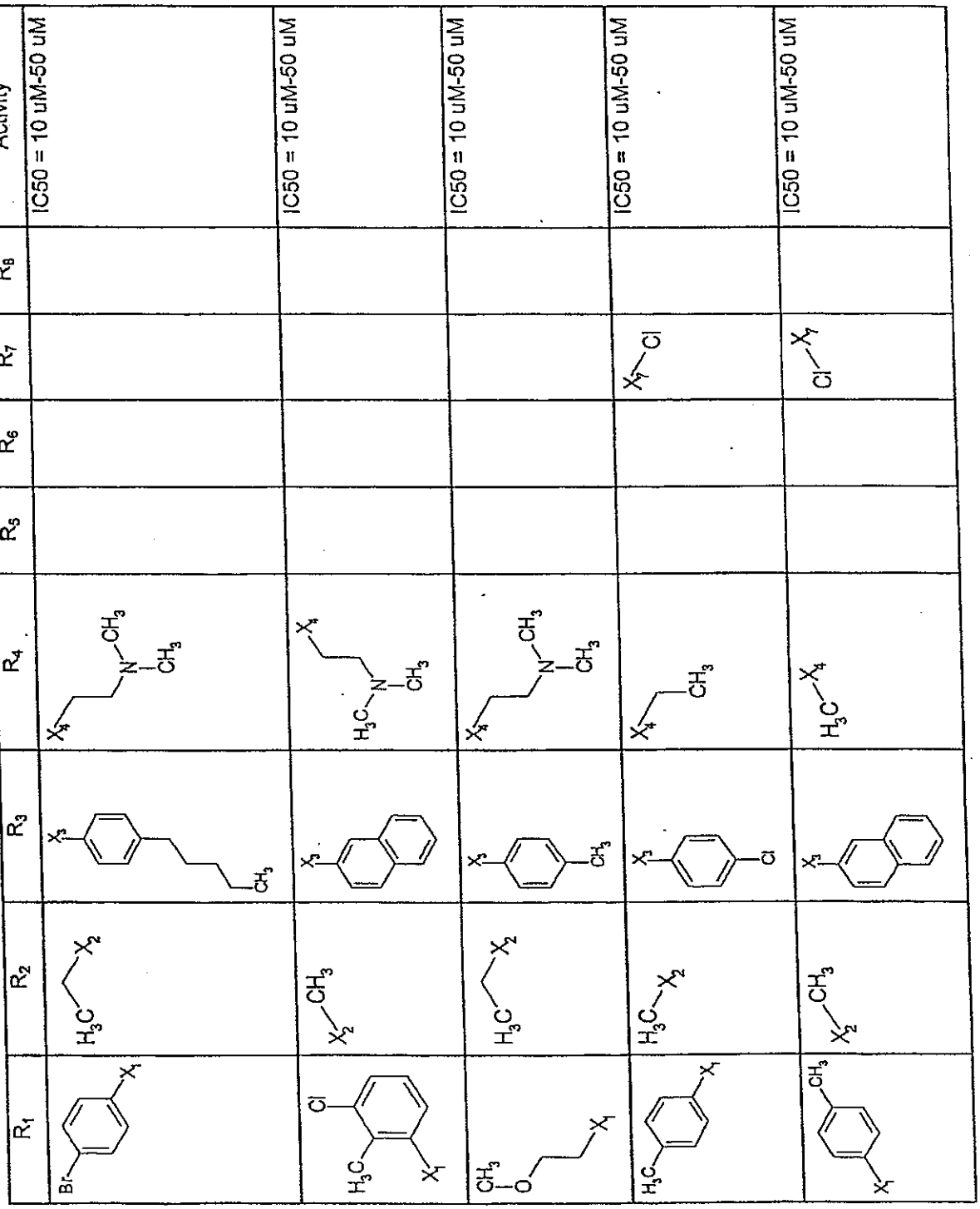
Figure 3 (continued)

R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)

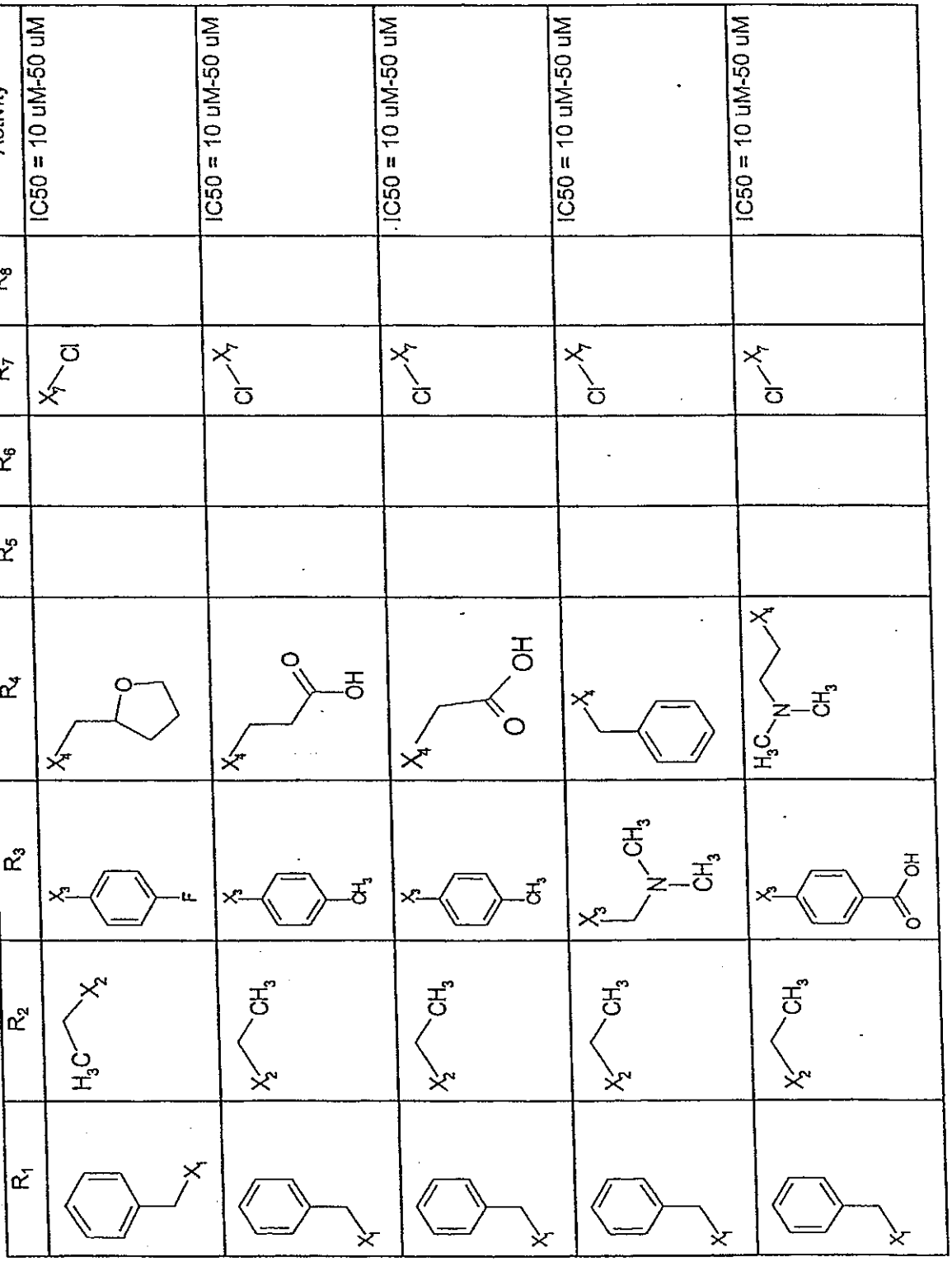
R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM

Figure 3 (continued)



R_1	R_2	R_3	R_4	R_5	R_6	R_7	R_8	Activity
								IC50 = 10 uM-50 uM
								IC50 = 10 uM-50 uM
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Figure 3 (continued)

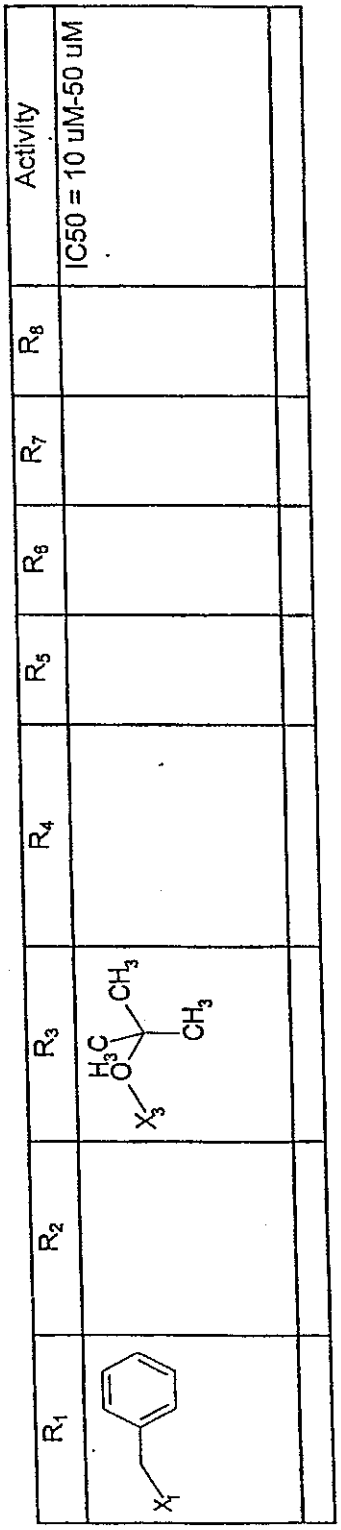
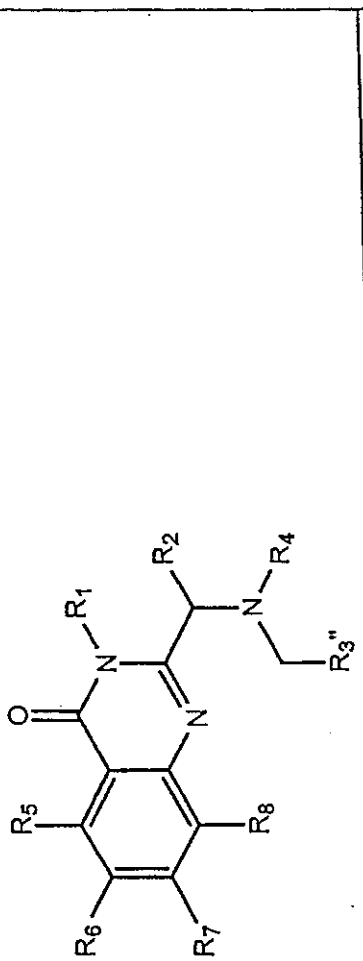


Figure 3 (continued)



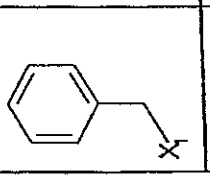
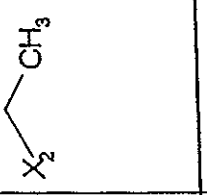
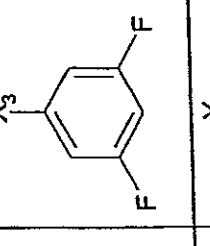
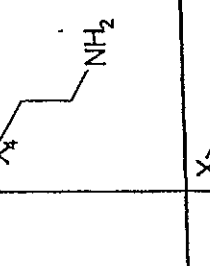
R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

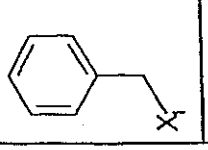
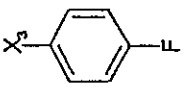
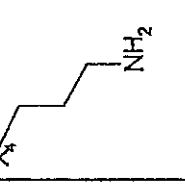
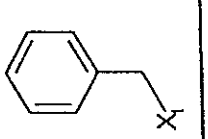
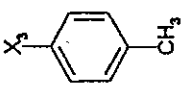
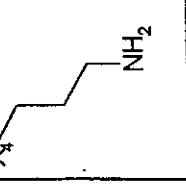
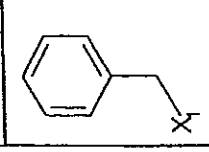
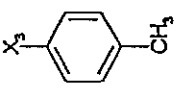
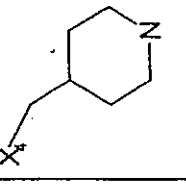
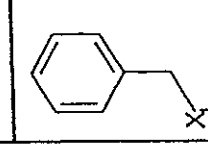
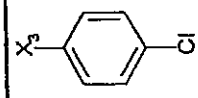
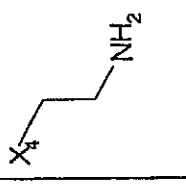
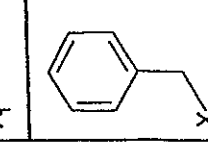
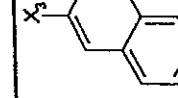
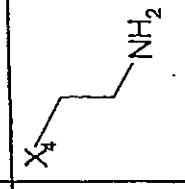
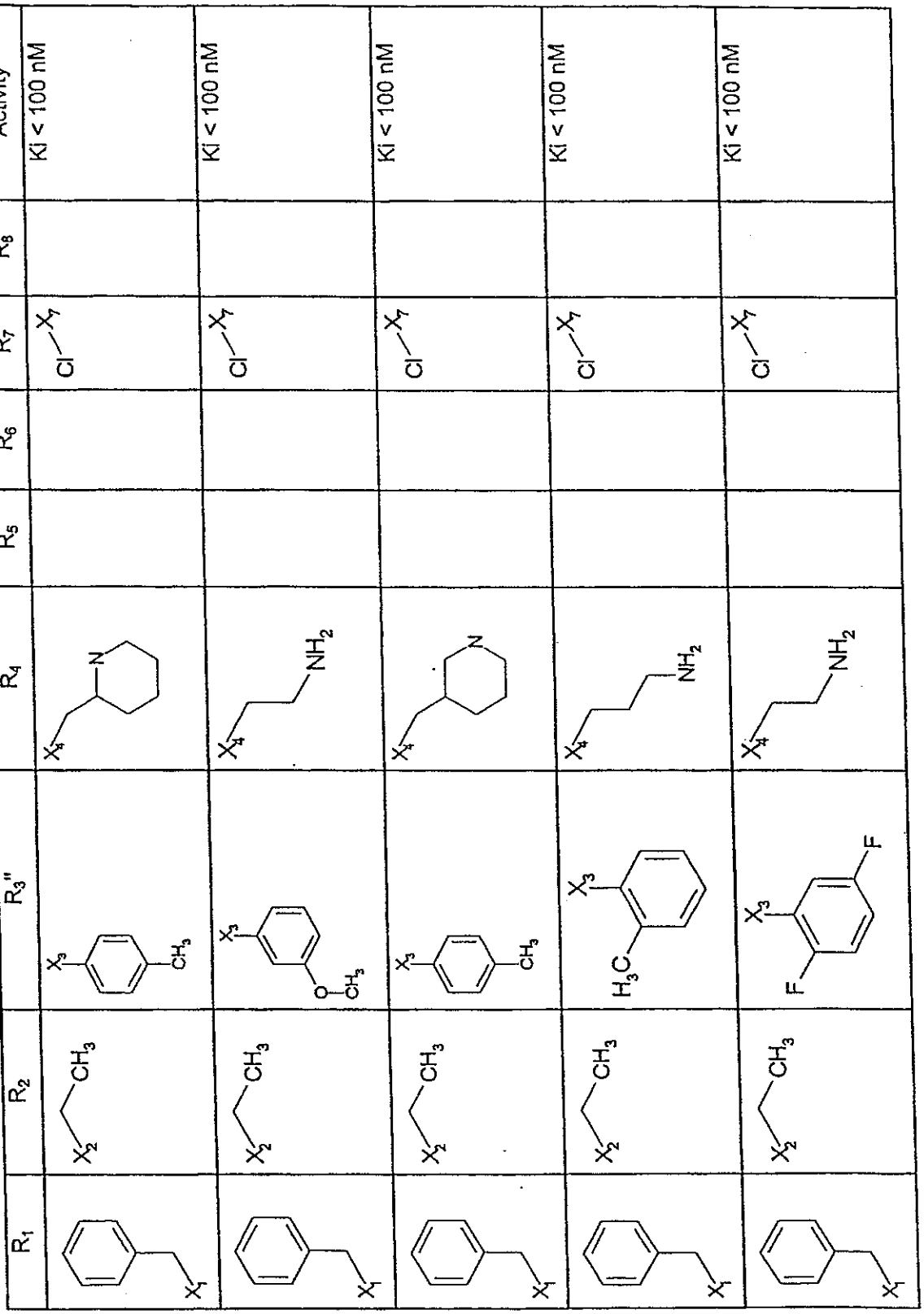
R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

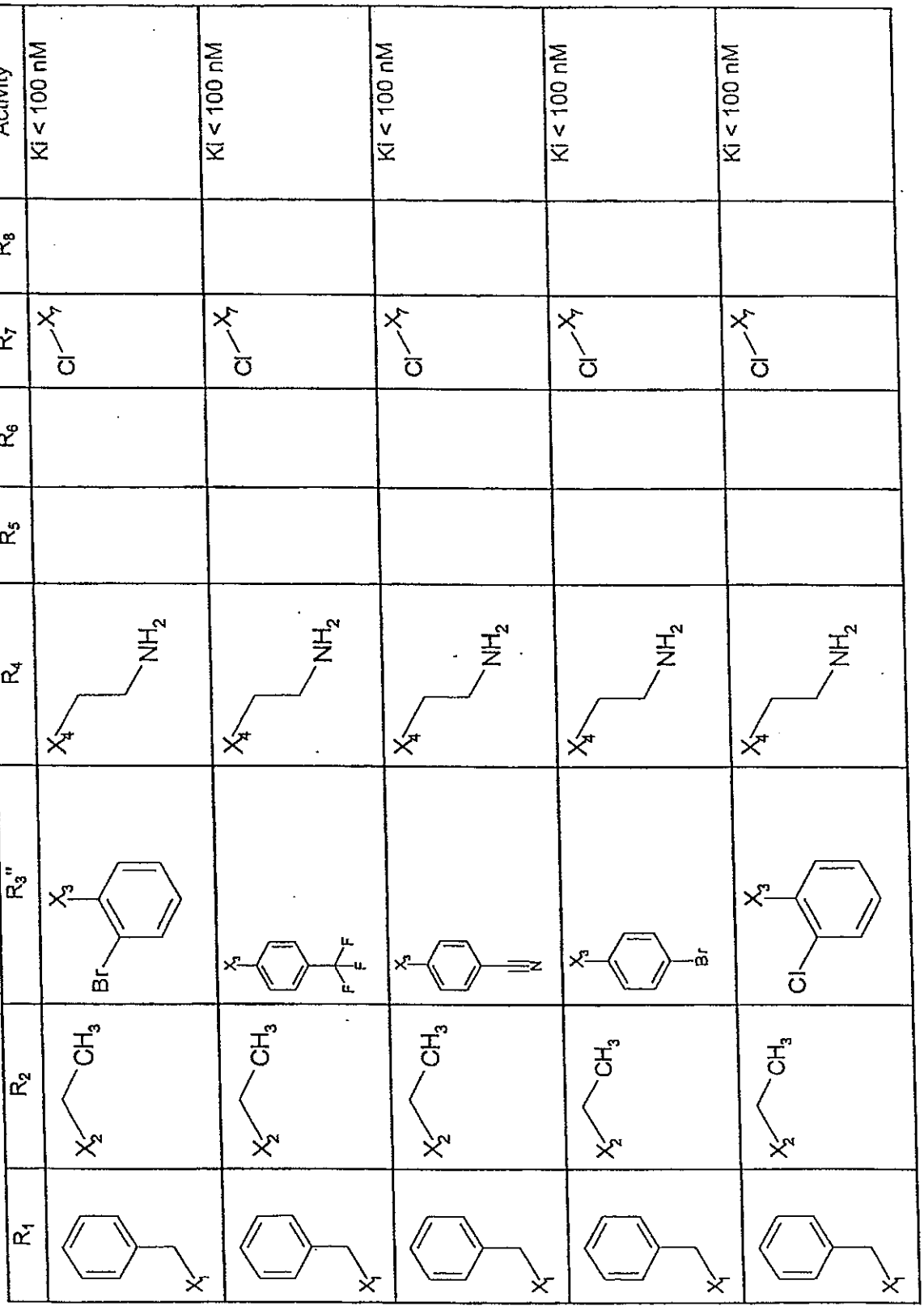


R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)



R_1	R_2	R_3''	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R_1	R_2	R_3''	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

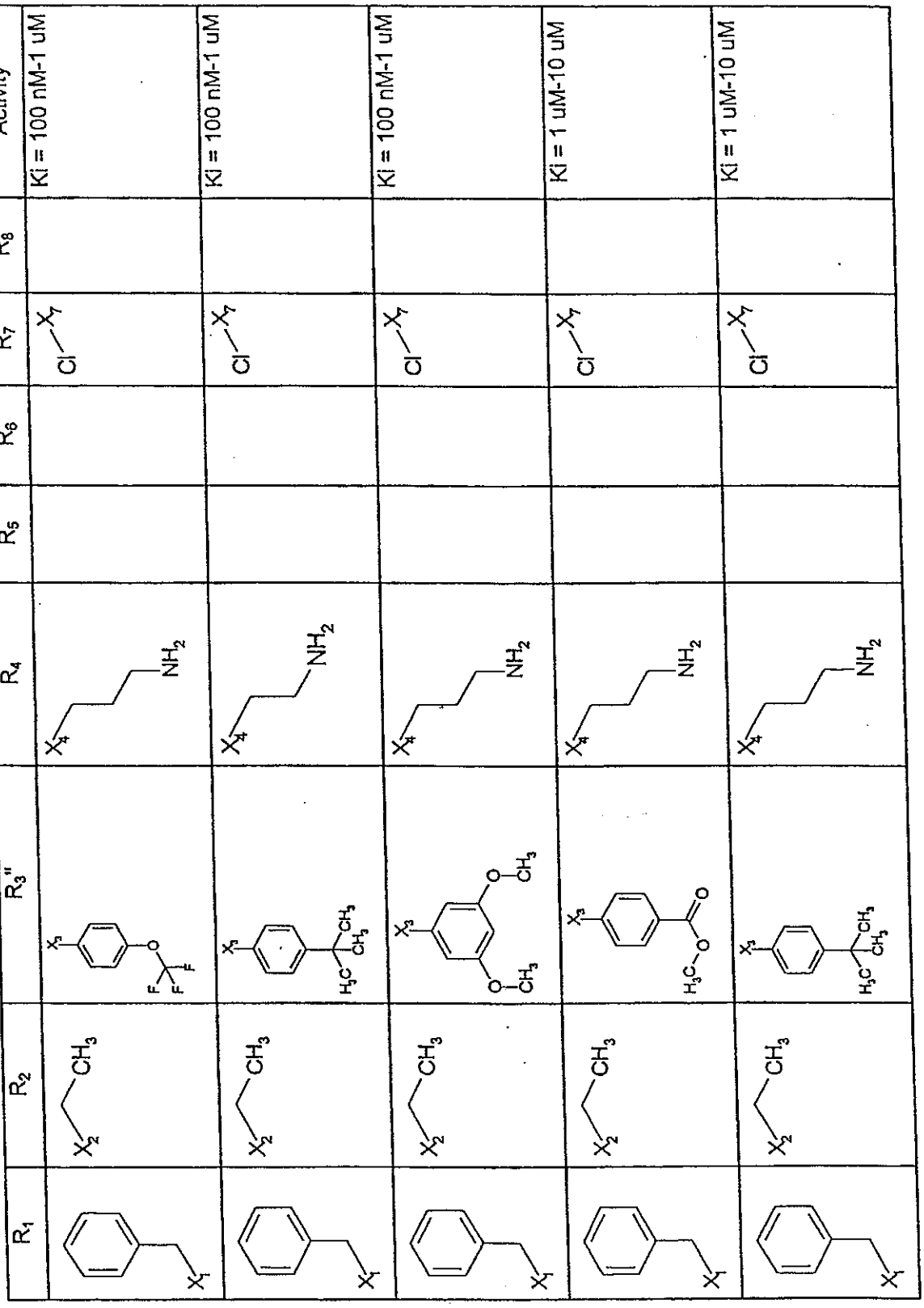
Figure 3 (continued)

R_1	R_2	R_3''	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM

Figure 3 (continued)

R_1	R_2	R_3"	R_4	R_5	R_6	R_7	R_8	Activity
								Ki < 100 nM
								Ki < 100 nM
								Ki < 100 nM
								Ki = 100 nM-1 uM
								Ki = 100 nM-1 uM

Figure 3 (continued)



R_1	R_2	R_3''	R_4	R_5	R_6	R_7	R_8	Activity
								Ki = 100 nM-1 uM
								Ki = 100 nM-1 uM
								Ki = 100 nM-1 uM
								Ki = 1 uM-10 uM
								Ki = 1 uM-10 uM

Figure 4: Asymmetric Synthesis

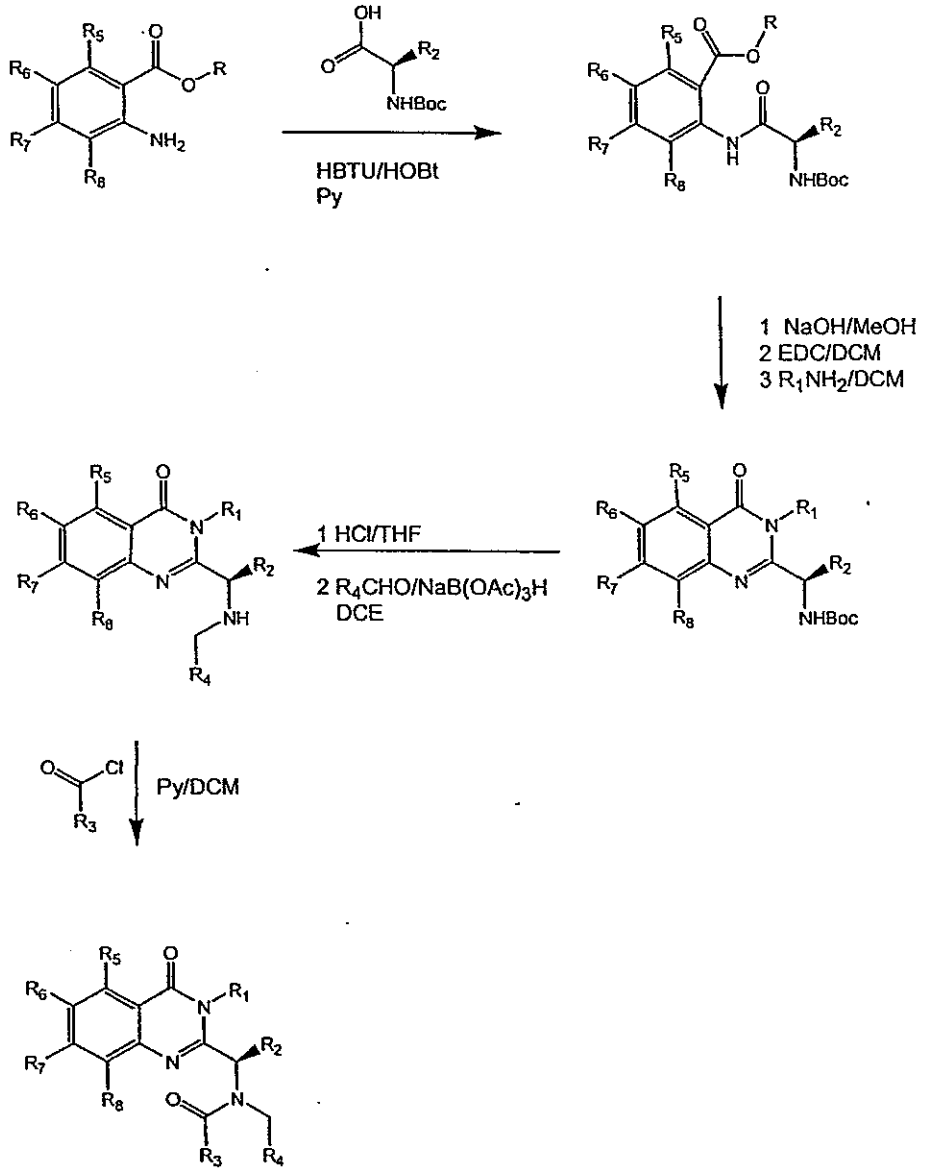


Figure 5

Figure 5a: Sulfonamide Synthesis

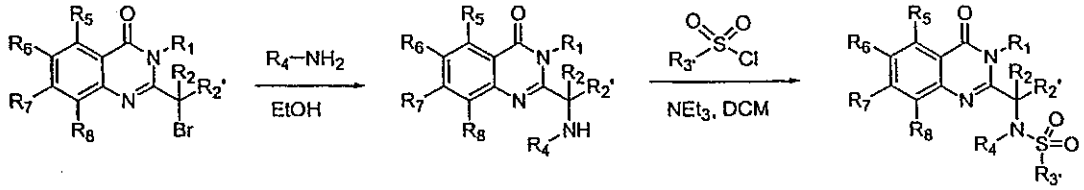


Figure 5b: Carbamate Synthesis

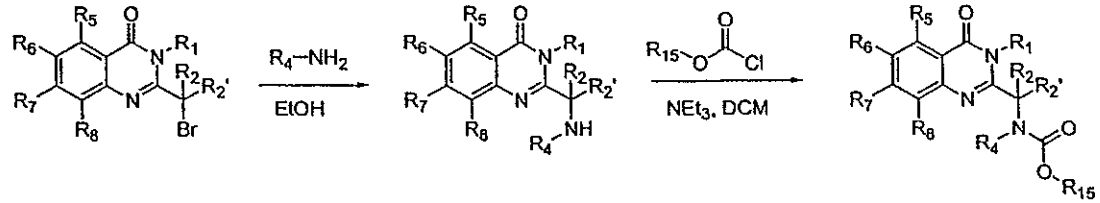


Figure 5c: Urea Synthesis

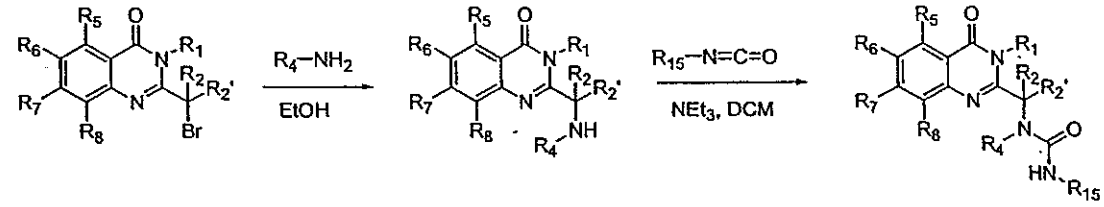


Figure 5d: Primary and Secondary Amine R4 Synthesis

